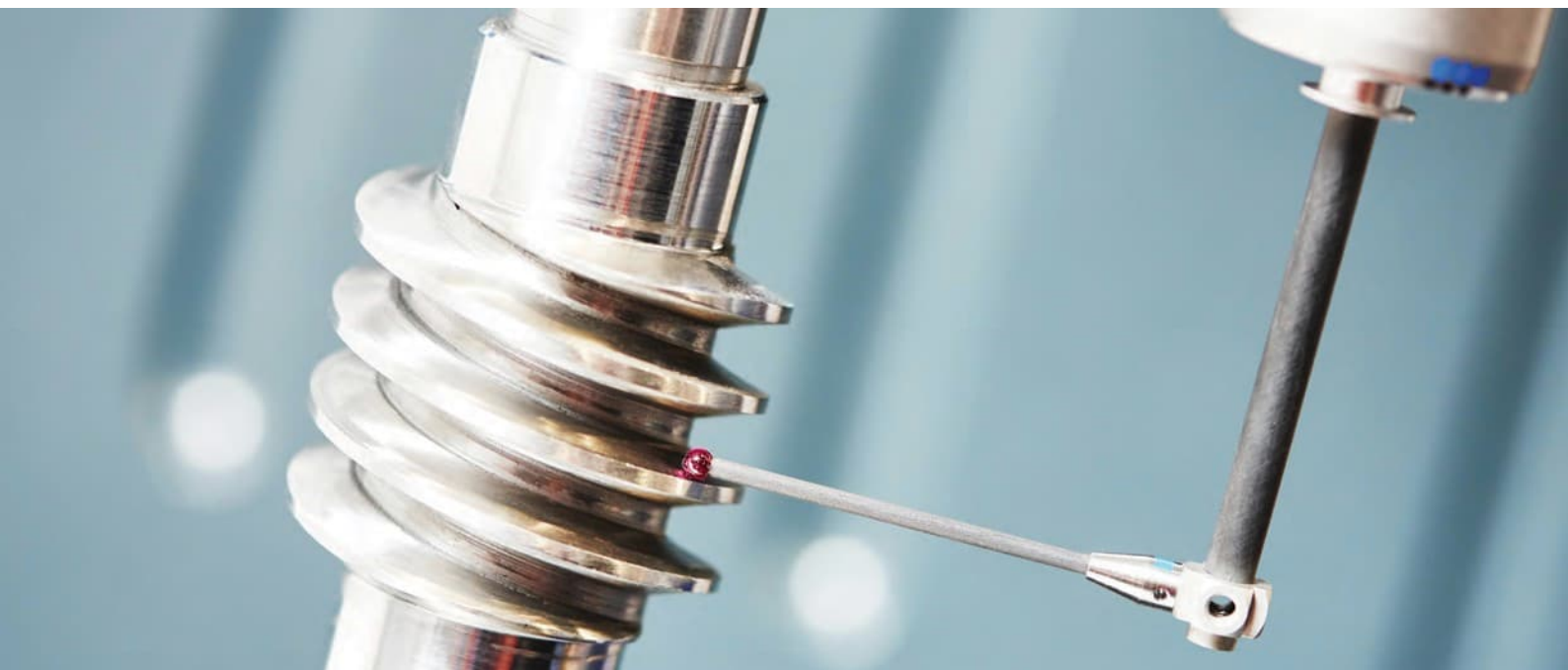


# Calibration Services

Length and angle

**VTT MIKES**





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VTT Technical Research Centre of Finland Ltd  
P.O. Box 1000 (Vuorimiehentie 3, Espoo), FI-02044 VTT  
Tel. +358 20 722 111  
[www.vttresearch.com](http://www.vttresearch.com)

## VTT MIKES

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# Scanning probe microscopy measurements

Bruno Sauvet, Research Scientist  
Tel. +358 50 432 6443  
[bruno.sauvet@vtt.fi](mailto:bruno.sauvet@vtt.fi)

Virpi Korpelainen, Senior Scientist  
Tel. +358 50 410 5504  
[virpi.korpelainen@vtt.fi](mailto:virpi.korpelainen@vtt.fi)

VTT MIKES, Tekniikantie 1,  
FI-02150 Espoo, Finland

## Nanometre scale measurements

Development and research in nanotechnology has increased the need for accurate measurements in research institutes and industry. Different kinds of Scanning Probe Microscope (SPM) measurements are commonly used in many institutes and companies. In order to guarantee accurate and reliable dimensional measurements at nanometre range, MIKES has a traceably calibrated Atomic Force Microscope (AFM). Thus, MIKES can provide customers with traceable measurements also at nanometre range. MIKES provides accurate AFM measurement services to match the needs of customers. In addition, we calibrate SPM transfer standards.

Scale errors of uncalibrated SPMs typically range from 2 % to 20 %. In addition, measurement errors may cause distortions in the measured figure, which might be difficult to detect from the figure. Therefore, the device has to be calibrated. New, more advanced SPMs have increased measurement precision, but the development does not remove need for calibration. Especially in all quantitative form measurements, the measurements should be traceable to the definition of the metre. Usually, SPMs are calibrated by using calibrated transfer standards.

## Jupiter XR

We have a state-of-the-art scanning probe microscope for customer measurements. In addition to topography several other functional properties can be measured: electrical and mechanical properties. The available measurement modes are listed in table 1.



Figure 1. Jupiter XR measurements.

## Large sample SPM measurements

Typically, SPM measurements are for small samples and small measurement range. For large measurement area the images can be stitched to larger images. There are challenges in the stitching algorithms. Therefore, we have integrated 2D laser interferometer to the Jupiter coarse movement to allow easy and accurate stitching of the images. The interferometric position measurement allows combining the images over 200 mm x 200 mm area.

## Metrological AFM

Metrological AFM (MAFM) is an atomic force microscope with interferometric position measurement. The MAFM is mostly used for calibration of step height standards but can be used also for other measurement requiring the highest traceability.

## Measurement uncertainty

Measurement uncertainty depend on the measured structure. Sub-nanometre uncertainties can be reached in the measurements.

Table 1. The SPM modes available for customer measurements.

<b>AC air (tapping mode)</b>
Dynamic AFM technique imaging the sample topography by scanning the surface with an oscillating cantilever.
<b>AM / FM</b>
The cantilever is simultaneously driven at 1 <sup>st</sup> and 2 <sup>nd</sup> eigenmode (topography and elasticity, respectively).
<b>Fast force map</b>
Deflection technique allowing users to acquire data (topography, adhesion, mechanical & electrical properties, ...)
<b>Kelvin probe microscopy (KPM)</b>
Measures a potential difference ( $V_{CPD}$ ) of the contact between the probe tip and the sample.
<b>Electrostatic force microscopy (EFM)</b>
This mode measures a frequency shift due to the electric force gradient between the probe tip and the sample.
<b>Piezo force microscopy (PFM)</b>
Measures the vertical piezo polarization of the sample.
<b>Magnetic force microscopy (MFM)</b>
Measures the magnetic field gradient of a sample.
<b>Conductive AFM (CAFM -ORCA)</b>
This mode is a contact mode. A current will pass through the chuck and the AFM measures the current through the sample. Two types of measures are possible: Imaging (scanning mode) and spectroscopy (pick a point curve).
<b>Scanning capacitance microscopy (SCM)</b>
In this mode, the set (tip + oxide layer + semi-conductor sample) responds as a MOS capacitor.



Figure 2. Interferometrically traceable MIKES metrological AFM.

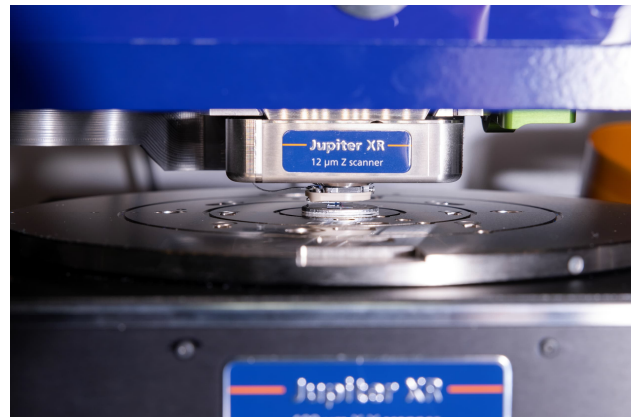


Figure 3. The Jupiter XR large sample AFM.

## References

- V. Korpelainen, J. Seppä, and A. Lassila, "Design and characterization of MIKES metrological atomic force microscope", *Precision Engineering* **34**, 735–744 (2010) <https://doi.org/10.1016/j.precisioneng.2010.04.002>.
- V. Korpelainen, J. Seppä, and A. Lassila, "Measurement strategies and uncertainty estimations for pitch and step height calibrations by metrological atomic force microscope", *Journal of Micro/Nanolithography, MEMS, and MOEMS* **11**, 011002 (2012) <https://doi.org/10.1117/1.JMM.11.1.011002>.

# Measurements for photonics industry

Bruno Sauvet, Research Scientist  
Tel. +358 50 432 6443  
[bruno.sauvet@vtt.fi](mailto:bruno.sauvet@vtt.fi)

Virpi Korpelainen, Senior Scientist  
Tel. +358 50 410 5504  
[virpi.korpelainen@vtt.fi](mailto:virpi.korpelainen@vtt.fi)

VTT MIKES, Tekniikantie 1,  
FI-02150 Espoo, Finland

## Introduction

Photonics is fast growing field and especially development of Augmented Reality (AR) optics require new more accurate characterisation methods. At VTT MIKES we can provide a wide range of measurements for photonic industry: DOEs, Waveguides & waveguide couplers. For DOEs the typical measurands are period, grating parameters and angular position and homogeneity. For waveguides the measurands are thickness & thickness variation, flatness and parallelism. All measurements are traceable to the SI unit system which guarantees comparability with other measurements and e.g. simulations.

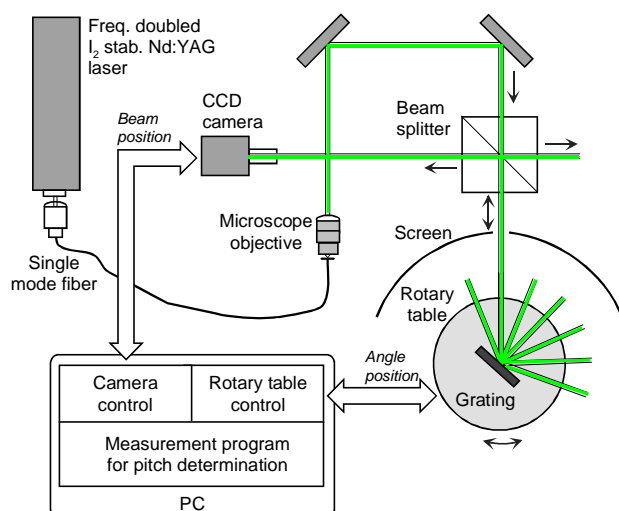


Figure 1. The VTT MIKES laser diffractometer

## Grating pitch & homogeneity

A high accuracy laser diffractometer can be used to measure average grating pitch and homogeneity of the pitch with uncertainty of tens of picometers depending on the pitch and sample quality.

Grating homogeneity can be measured semiautomatically on 50 mm × 50 mm area on 100 mm disc. The measurement can be done in hundreds or thousands measurement points.

## Grating orientation

Relative angles between the gratings are important e.g. in waveguide couplers.

## Thickness, thickness variation, flatness, and parallelism

The parameters are important in waveguides and other optical components. Fizeau interferometer can be used to measure thickness and its variations.

## Other grating parameters

We have two different types of scatterometers available for measuring grating parameters such as period, fill ratio, height, side wall angles, corner rounding, defects, etc. Goniometric scatterometer measures light intensity as a function of diffraction angle and spectral scatterometer measures spectral intensity of reflected/transmitted light at a fixed angle.

## Microscopic methods

Different types of microscopes can be applied for grating measurements. The available methods are atomic force microscopes (AFM), scanning electron microscopes (SEM), coherence scanning microscope and optical microscopes.

## Custom measurements

We have a lot of knowledge and possibilities to build customised measurement systems for various custom needs.

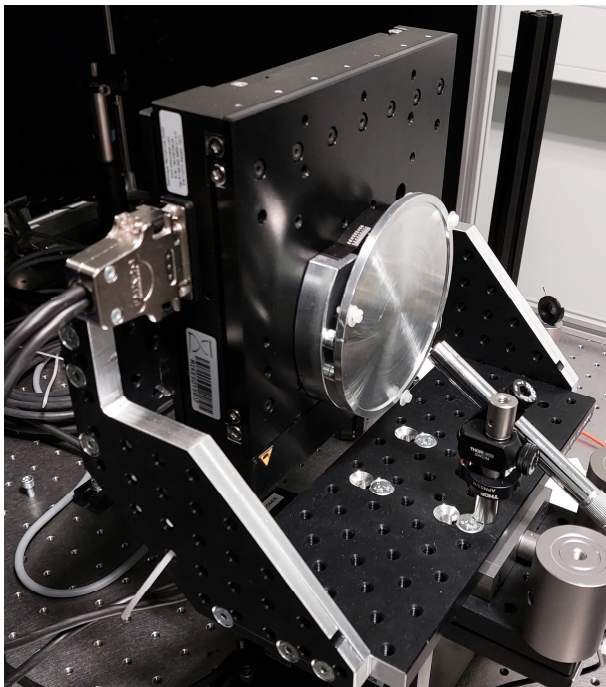


Figure 2. Sample holder for 100 mm wafer with xy positioning for measurements of several grating areas or grating homogeneity measurement.

## Measurement uncertainty

Standard uncertainty of the rating pitch measurement depends on the pitch and sample quality. The lowest uncertainty for the pitch measurement is a few picometers.

Standard uncertainty for the relative grating orientation is 1 arcs.

Table 1. Methods for measurements of photonic industry.

<b>Laser diffractometer</b>
– Grating pitch
– Grating pitch homogeneity
<b>Angle measurements</b>
– Grating orientation
<b>Scatterometry</b>
– Grating pitch
– Duty cycle, linewidth
– Haze
<b>Interferometric methods</b>
– Thickness & thickness variation
– Flatness and parallelism
– Parallelism
– Refractive index
<b>Microscopy</b>
– Topography
– Height, linewidth, fill factor
– Side wall angle, blaze angle
<b>Custom measurements</b>
– Agreed together with the customer

## References

V. Korpelainen, A. Iho, J. Seppä, and A. Lassila, "High accuracy laser diffractometer: angle-scale traceability by the error separation method with a grating", *Measurement Science and Technology* **20**, 084020 (2009), <https://doi.org/10.1088/0957-0233/20/8/084020>.

# Characterization of nanoparticles

Virpi Korpelainen, Senior Scientist  
Tel. +358 50 410 5504  
[virpi.korpelainen@vtt.fi](mailto:virpi.korpelainen@vtt.fi)

VTT MIKES  
Tekniikantie 1, FI-02150 Espoo, Finland  
Tel. +358 20 722 111

Nanoparticles are widely used in many applications. Accurate characterization of the nanoparticles is important in research, production and applications in several fields including industry, health, safety and related regulation. At VTT MIKES, the particles can be characterized using two different methods: Dynamic Light Scattering (DLS) and atomic force microscopy (AFM). The measurements are traceable to the definition of the metre via VTT MIKES interferometrically traceable metrological atomic force microscope (IT-MAFM). Both methods have advantages and limitations. DLS is fast method and the results are statistically representative. In DSL measurements, even a small number of large particles can prevent detection of small particles. AFM can be used to measure both size and shape of single particles. The disadvantage of AFM measurements is that only limited number of particles can be measured which leads to poor statistics. Tip sample interaction is important especially when measuring small particles. In addition, sample preparation might be challenging.

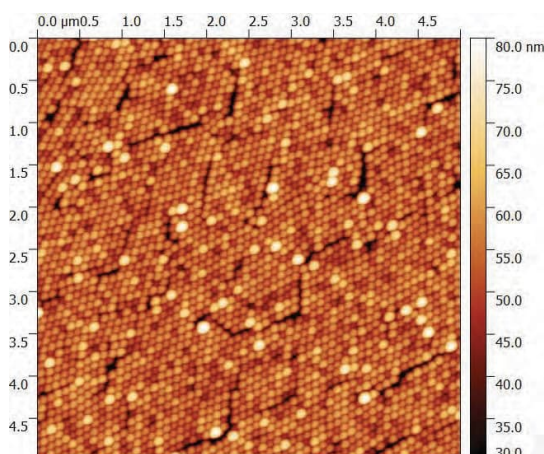


Figure 1. AFM image of 100 nm nanoparticles.

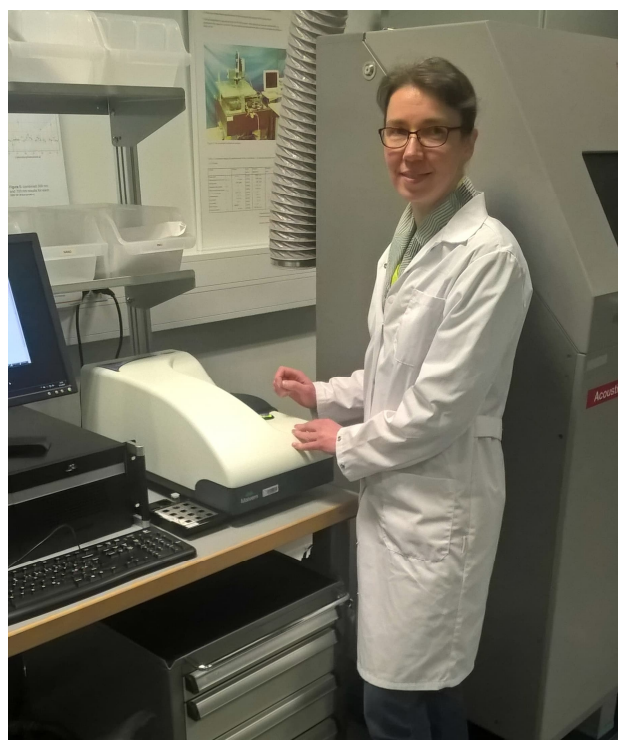


Figure 2. DLS measurements.

Table 1. VTT MIKES has two instruments suitable for nanoparticle measurements.

Instrument	Zetasizer Nano	PSiA XE-100
Measurement method	DLS	AFM
Measurands	Size distribution Zeta potential	Size Shape
Measurement range	0.3 nm – 10 μm	5 nm – 5 μm
Measurement uncertainty	2 %	from 1 nm

## Zetasizer Nano

Dynamic Light Scattering is used to measure particle and molecule sizes. This technique measures the diffusion of particles moving under Brownian motion, and converts this to size and a size distribution using the Stokes-Einstein relationship.

Laser Doppler Micro-electrophoresis is used to measure zeta potential. An electric field is applied to a solution of molecules or a dispersion of particles, which then move with a velocity related to their zeta potential.

## Services for nanoparticle characterization

- Nanoparticle size and shape measurements using AFM
- Nanoparticle size distribution in solution using DLS
- Nanoparticle surface charge (Zeta-potential) measurements in solution

## Atomic force microscopy (AFM)

An AFM uses a cantilever with a very sharp tip to scan over a sample surface. As the tip approaches the surface, the close-range, attractive force between the surface and the tip cause the cantilever to deflect towards the surface. However, as the cantilever is brought even closer to the surface, such that the tip makes contact with it, increasingly repulsive force takes over and causes the cantilever to deflect away from the surface.

In AFM images the topography of a sample surface by scanning the cantilever over a region of interest. The raised and lowered features on the sample surface influence the deflection of the cantilever, which is monitored by a position-sensitive photo diode (PSPD). By using a feedback loop to control the height of the tip above the surface the AFM can generate an accurate topographic map of the surface features.

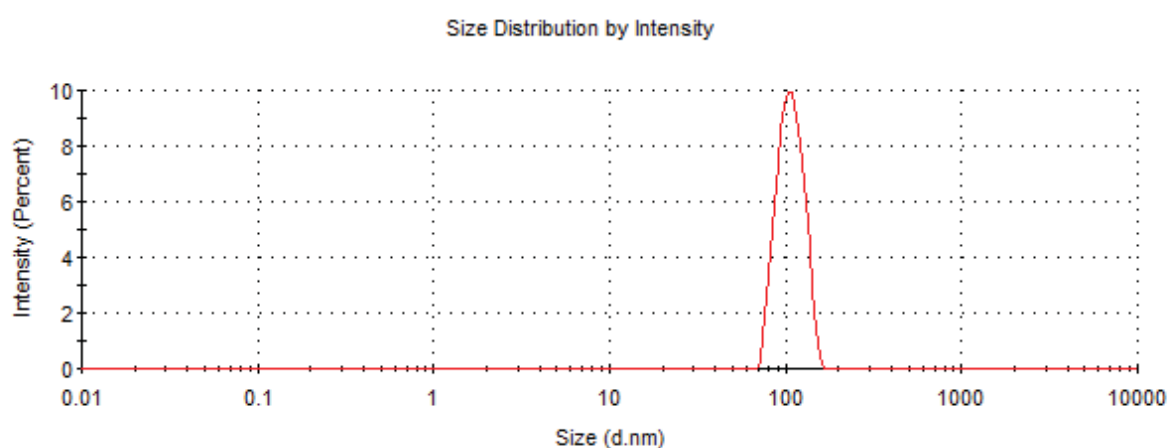


Figure 3. DLS results of ~100 nm nanoparticles.

# Calibration of laser interferometers

Jeremias Seppä, Senior Scientist  
Tel. +358 50 410 5503  
[jeremias.seppa@vtt.fi](mailto:jeremias.seppa@vtt.fi)

Jarkko Unkuri, Research Scientist  
Tel. +358504105506  
[jarkko.unkuri@vtt.fi](mailto:jarkko.unkuri@vtt.fi)

VTT MIKES  
Tekniikantie 1, FI-02150 Espoo, Finland  
Tel. +358 20 722 111

Laser interferometers together with gauge blocks are the most important measurement standards in modern length metrology. At 1980s a common understanding was that laser interferometers are accurate and hence do not need any calibration. However, ever-increasing demand for accuracy and long experience on usage of laser interferometers have shown that it is necessary to calibrate laser interferometers, also. At VTT MIKES, we have traceable procedures to calibrate laser interferometers. The calibration of laser interferometers improves their reliability and accuracy essentially.



Figure 1. Functional testing of a laser interferometer.

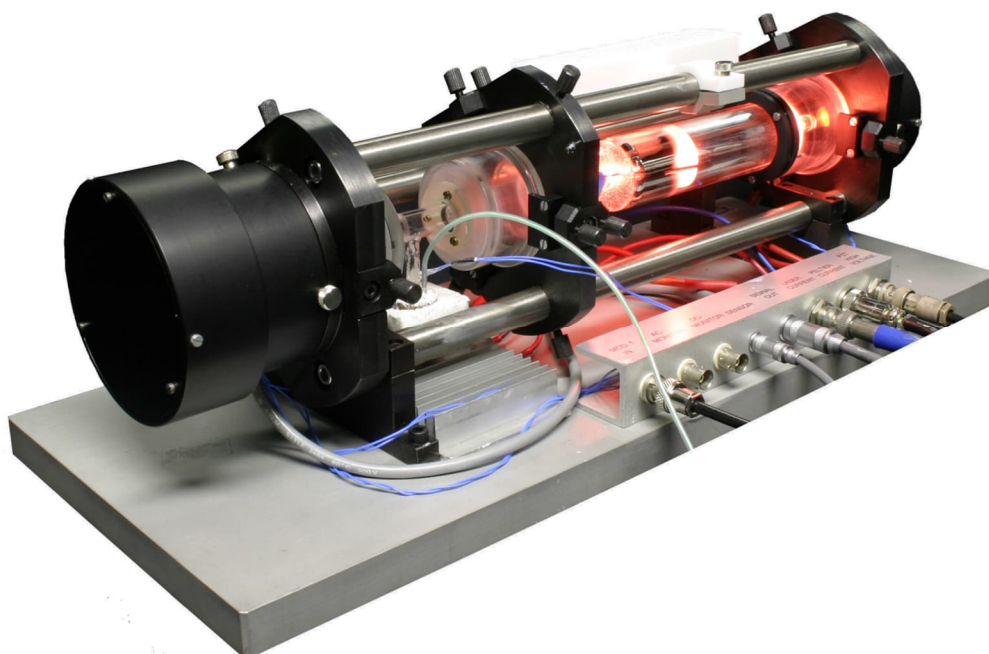


Figure 2. An iodine-stable HeNe-laser used for the practical realisation of the metre.

## Calibration procedure

### Calibration of laser frequency

The vacuum wavelength of lasers used in laser interferometers is calibrated using iodine-stabilised lasers. Traceability to the definition of the metre is guaranteed as frequencies (vacuum wavelength) of the iodine-stabilised lasers are determined by an optical frequency comb referenced to an atomic clock.

VTT MIKES maintains the following lasers that are locked to iodine absorption lines according to international recommendations: He-Ne lasers at wavelengths: 633 nm (Figure 2) and 543.5 nm and a Nd:YAG-laser at 532 nm. These laser have a relative frequency uncertainty better than  $10^{-10}$  (expanded uncertainty,  $k=2$ ).

The frequency of the laser under calibration is compared to the frequency of an iodine-stabilized laser. The calibration includes a long-term frequency (vacuum wavelength) calibration and repeatability measurements. Moreover, the frequency difference of the horizontally and vertically polarised lights is determined and the separation of the polarisation planes inspected. Together these measurements provide good indication of the frequency stability of the laser under calibration. Lasers that operate at wavelengths not reachable by iodine-stabilized lasers can be calibrated using a frequency comb.

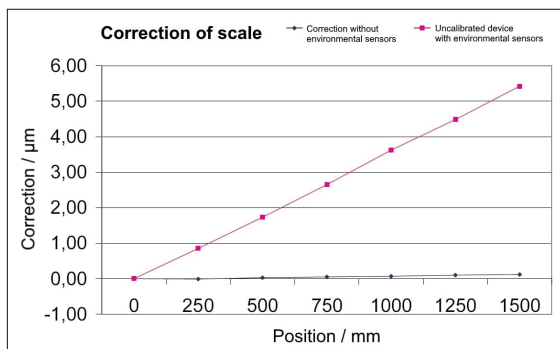


Figure 3. Errors in environmental sensors can have remarkable effects on the readings of a laser interferometer.

Table 1. Uncertainty of calibration.

Quantity	Measuring range	Uncertainty ( $k=2$ )
Wavelength	633 nm; 543.5 nm; 532 nm	$\sim 10^{-9}$ (relative)
Air pressure	970...1050 hPa (730 ... 790 mmHg)	40 Pa
Air temperature	17...25 °C	0.10 °C
Material temperature	15...25 °C	0.050 °C
Combined uncertainty	0...30 m	$Q[0,02 \mu\text{m}, 05\text{E-}6 \text{ L}]$

### Calibration and functional testing of environmental sensors

In addition to laser vacuum wavelength calibration, the environmental sensors are calibrated and their operation tested. These measurements are necessary to achieve the naturally good measurement accuracy of a laser interferometer. Especially, by calibrating the environmental sensors order of magnitude better measurement accuracy can be achieved for a laser interferometer.

The calibration of environmental sensors includes the calibration of air temperature sensors, atmospheric pressure sensors and material temperature sensors. The functional testing is performed in a temperature-stabilised laboratory room by measuring the locations of a moving carriage equipped with a retroreflector with the laser interferometer under calibration and with a reference laser interferometer (Figure 1). In these measurements, both laser beams travel through the same optical components and data is collected with and without the environmental sensors operating. In addition, the angle scale is tested using a reference laser. If necessary, the quality of the optical components is tested with a flatness interferometer.

If the readings of the environmental sensors deviate remarkably from readings of the reference instruments, they should be adjusted. By adjusting, the accuracy of the laser interferometer can easily be improved (Figure 3), e.g., the adjustment is relatively easy to perform in Agilent laser interferometers.

## Traceability

The frequencies of the iodine-stabilised lasers that are the national measurement standards of length are determined using an optical frequency comb referenced to VTT MIKES atomic clocks. Instruments used in the calibration of environmental sensors are calibrated in the corresponding national standards laboratories. Thus, the measurements are traceable to the corresponding definitions of the units.

# Interferometric calibration of gauge blocks

Antti Lassila, Research Team Leader  
Tel. +358 40 767 8584  
[antti.lassila@vtt.fi](mailto:antti.lassila@vtt.fi)

VTT MIKES  
Tekniikantie 1, FI-02150 Espoo, Finland  
Tel. +358 20 722 111

## Calibration of gauge blocks

Gauge blocks are the most important measurement standards of length in industry. Interferometric measurement of gauge blocks provides an absolute calibration method. By using interferometers, the practical realisation of the metre is transferred to a gauge block via the calibrated wavelength of the frequency-stabilised laser used in the interferometer. Gauge blocks calibrated by comparison must be traceable to gauge blocks calibrated by interferometry. The length of a gauge block is defined in an ISO standard as the distance from the centre of the gauge face to an auxiliary reference plane wrung to the other end of the gauge block at 20 °C temperature and at 1013.25 hPa barometric pressure. Gauge block sets calibrated by interferometry give a lower uncertainty for mechanical calibrations e.g. in accredited calibration laboratories.

## Interferometers at VTT MIKES

VTT MIKES have gauge block interferometers for short (0...300 mm) and for long (100...1000 mm) gauge blocks and end standards. The interferometers are located in a laboratory room having well stabilised environmental conditions and they are equipped with temperature, humidity and pressure sensors. Low uncertainties for refractive index of air and for thermal expansion compensation can be achieved with a precise control and monitoring of the environmental conditions. Difference in surface roughness between the gauge block face and the reference plane is measured and corrected for in results. The parallelism and flatness of the surfaces can be measured, also.

The VTT MIKES PSIGB interferometer for short gauge blocks (Fig. 1) uses stabilised He-Ne lasers at 633 nm and 543.5 nm. The interferometer is equipped with a large wringing bed, which enables fast and automated calibration of even 14 gauge blocks in sequence. In the Tesa interferometer, the gauge blocks are positioned vertically.



Figure 1. VTT MIKES PSIGB gauge block interferometer and wringing station.

The long gauge block interferometer (Fig. 2) utilises white light and 633-nm laser light interference patterns. By using white light, beforehand knowledge of the length of the end standard is not required. The end standards and gauge blocks are positioned horizontally and supported at the Bessel points in such a way that the weight of the reference plane is compensated for.

## Calibration services

Gauge block interferometers can be used to measure even other artefacts whose surfaces are flat and smooth enough; e.g., to determine the thermal expansion coefficient of ceramic sealings and to measure the air gap between two parallel glass plates. Interferometric calibration sets also demands for gauge blocks: their end surfaces must be parallel, flat and without scratches. VTT MIKES calibrates gauge blocks of grades K (00) and 0 and end standards, e.g. quartz metres, according to the following table.

## Traceability

The regular calibration of length standards and length measuring equipment is a necessary part of measurement quality control. Traceable calibrations and knowledge on the measurement uncertainty are basic demands for good and constant quality. The traceability to gauge block calibrations is achieved by calibrating the wavelengths of lasers used in the interferometers against national measurement standards of length, iodine-stabilised He-Ne lasers. Measuring devices for temperature, humidity and pressure used in the interferometers are calibrated in corresponding VTT MIKES laboratories. The reliability of calibrations are verified by taking regularly part in international comparisons.

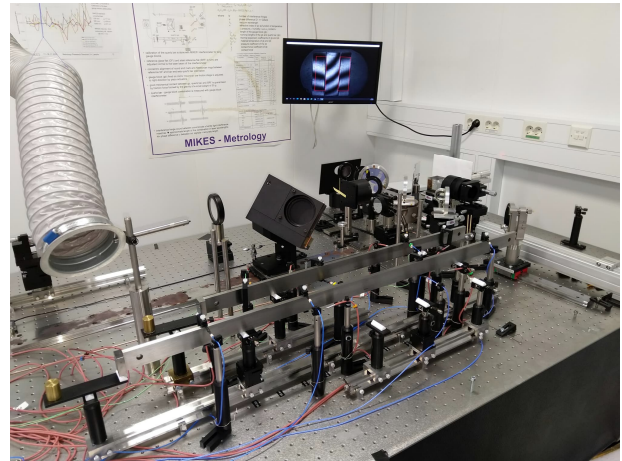


Figure 2. VTT MIKES length bar interferometer for calibration of long gauge blocks.

### References:

- Byman, V., & Lassila, A. (2015) MIKES' primary phase stepping gauge block interferometer. *Measurement Science and Technology* **26**(8), [084009].  
<https://doi.org/10.1088/0957-0233/26/8/084009>
- Ikonen, E. & Riski, K. (1993) Gauge-block Interferometer Based on One Stabilized Laser and a White-light Source, *Metrologia* **30**, 95–104.

Table 1. Calibration subjects and measurement uncertainties.

Device	Measurement range	Uncertainty ( $k=2$ )*
Gauge blocks, short	0.5 mm ... 200 mm	$Q[20 \text{ nm}, 190\text{E-}9 L]**$
Gauge blocks, short, length difference of GB pair	0.5 mm ... 100 mm	18 nm
Gauge blocks, long	100 mm ... 1000 mm	$Q[22 \text{ nm}, 110\text{E-}9 L]**$
Quartz meters	1000 mm	72 nm

$L$  = Nominal length

\*Uncertainty is often larger due to uncertainty caused by properties of the device under calibration

\*\*  $Q[x; y] = (x^2 + y^2)^{1/2}$

# Calibration of gauge blocks by mechanical comparison

Jyrki Ranta, Research Engineer  
Tel. +358 40 044 5887  
[jyrki.ranta@vtt.fi](mailto:jyrki.ranta@vtt.fi)

Juho Kukkohovi, Senior Research Technician  
Tel. +358 50 348 4200  
[juho.kukkohovi@vtt.fi](mailto:juho.kukkohovi@vtt.fi)

VTT MIKES  
Tekniikantie 1,  
FI-02150 Espoo, Finland  
Tel. +358 20 722 111

Mechanical comparison measurement is the most common way to determine the length of a gauge block. In this method, the length of the gauge block under calibration is compared to the length of a calibrated gauge block with same nominal length by using a specific comparator, Figure 1.

## Gauge block measurement

Comparison measurements of gauge blocks that have the same nominal length and that are of the same material are simple, reliable, fast and inexpensive. The method is also applicable to gauge blocks whose surfaces have been worn-out in use. VTT MIKES calibrates steel, hard metal, and ceramic gauge blocks in lengths 0.1 ... 1000 mm (Table 1). In calibration, we check the flatness of the surfaces and remove splatters that could prevent reliable use of the gauge blocks. A regular inspection of gauge blocks prevents a possible damage to affect the whole set. The use of uncalibrated gauge blocks in production quality control and in calibration of measurement equipment causes extra risks and costs

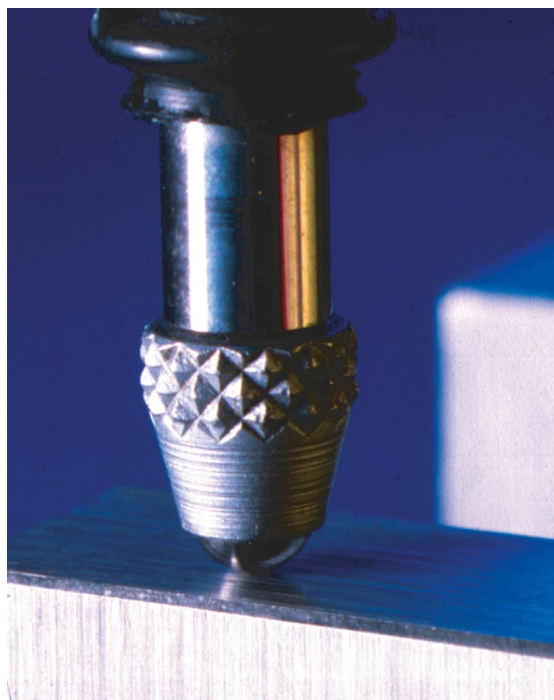


Figure 1. The sensor of the gauge block comparator identifies the location of the surface by using 0.6 Nm measurement force.

Table 1. Calibration of gauge blocks by mechanical comparison.

Measurement device	Measurement range	Uncertainty
Tesa gauge block comparator	0.1 mm ... 100 mm	$Q[50 \text{ nm}, 0.87E-6 L]$
MIKES comparator for long gauge blocks	100 mm ... 1000 mm	$Q[100 \text{ nm}, 0.87E-6 L]$

$L$  is the nominal length

## Traceability

The reference gauge blocks used in mechanical comparison measurements are regularly calibrated using VTT MIKES gauge block interferometers. The wavelengths of lasers used in these interferometers are calibrated by national measurement standard of length, iodine-stabilised He-Ne lasers

Table 2. Accuracy grades of ISO 3650:1998 standard.

Nominal length range mm		Calibration grade K mm		Grade 0 mm		Grade 1 mm		Grade 2 mm	
Lower length	Upper length	$\pm t_e$	$t_v$	$\pm t_e$	$t_v$	$\pm t_e$	$t_v$	$\pm t_e$	$t_v$
0.5	10	0.20	0.05	0.12	0.10	0.20	0.16	0.45	0.30
10	25	0.30	0.05	0.14	0.10	0.30	0.16	0.60	0.30
25	50	0.40	0.06	0.20	0.10	0.40	0.18	0.80	0.30
50	75	0.50	0.06	0.25	0.12	0.50	0.18	1.00	0.35
75	100	0.60	0.07	0.30	0.12	0.60	0.20	1.20	0.35
100	150	0.80	0.08	0.40	0.14	0.80	0.20	1.60	0.40
150	200	1.00	0.09	0.50	0.16	1.00	0.25	2.00	0.40
200	250	1.20	0.10	0.60	0.16	1.20	0.25	2.40	0.45
250	300	1.40	0.10	0.70	0.18	1.40	0.25	2.80	0.50
300	400	1.80	0.12	0.90	0.20	1.80	0.30	3.60	0.50
400	500	2.20	0.14	1.10	0.25	2.20	0.35	4.40	0.60
500	600	2.60	0.16	1.30	0.25	2.60	0.40	5.00	0.70
600	700	3.00	0.18	1.50	0.30	3.00	0.45	6.00	0.70
700	800	3.40	0.20	1.70	0.30	3.40	0.50	6.50	0.80
800	900	3.80	0.20	1.90	0.35	3.80	0.50	7.50	0.90
900	1000	4.20	0.25	2.00	0.40	4.20	0.60	8.00	1.00

Abbreviations in the table:

$t_e$  = deviation of length from nominal length

$t_v$  = variation in length

# 2D and 3D measurement of form and surface roughness

Björn Hemming, Senior Scientist  
Tel. +358 50 773 5744  
[bjorn.hemming@vtt.fi](mailto:bjorn.hemming@vtt.fi)

VTT MIKES  
Tekniikantie 1, FI-02150 Espoo, Finland  
Tel. +358 20 722 111

The manufacturing tolerances of modern products and the aim to high quality require the ability to measure different form measurands of small artefacts having complicated shapes. Examples of such form measurands are straightness, parallelism, radius of curvature and surface roughness. VTT MIKES measurement and calibration services using a computer controlled form and surface texture instrument provides one solution to these measurement problems.

## Form measurement

The form measurement instrument can detect form deviations even as small as 0.6 nm. Examples of typical form measurements are accurate measurements of straightness, inner and outer determinations of radius of curvatures and diverse dimensional measurements of small artefacts (Figure 1). These include determinations of grooves lengths and depths and inner and outer angle measurements. The most important technical specifications of the Taylor Hobson Form Talysurf instrument are gathered in table 1.

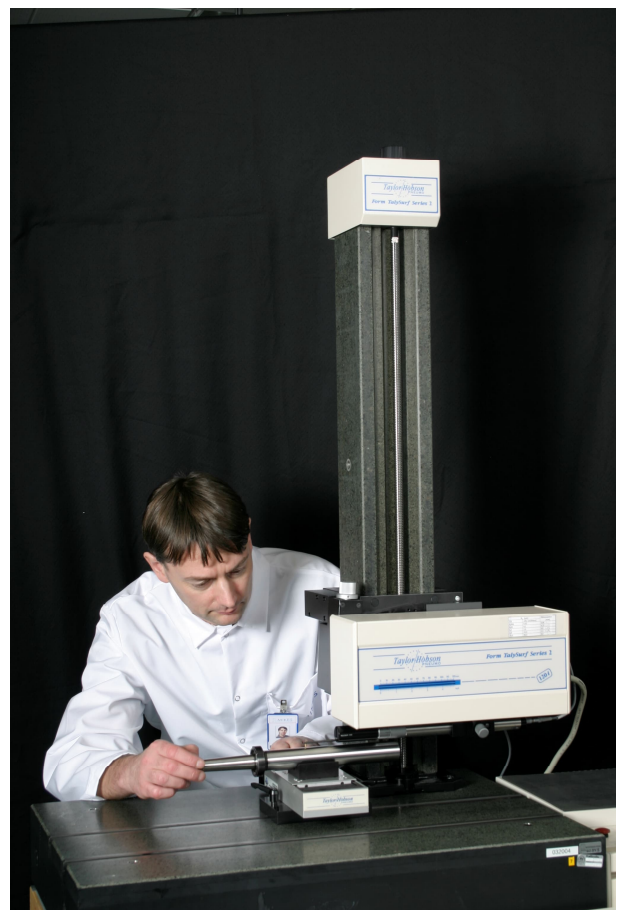


Figure 1. Straightness measurement on a cylindrical surface.

## Surface roughness measurements

In addition to calibration of surface roughness standards, the surface texture instrument at VTT MIKES is used for tasks related to quality control and product development. The surface roughness measurements at VTT MIKES are based on the following standards: ISO 5436-1 and ISO 4287.

## Measurement subjects

- traceable calibration of surface roughness standards
- diverse measurements in development of prosthesis in health care industry
- measurement of tribological samples
- profile measurements of blades of excavation machinery
- geometrical measurements in product development and quality control of electronic components
- product development and quality control measurements of metal packings and components in hydraulics and pneumatics.

## Traceability

Traceability to the form measurement instrument comes from interferometrically calibrated gauge blocks, a line scale, an optical flat and a sphere.

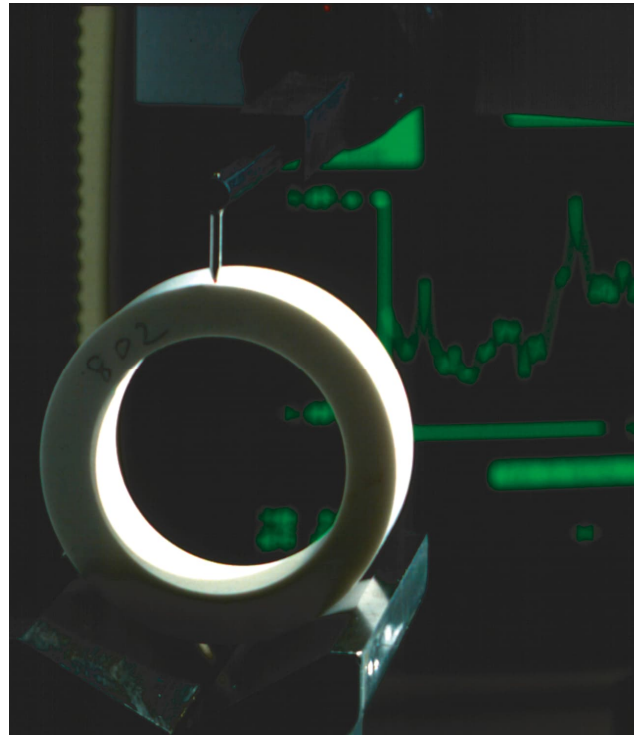


Figure 2. Measurement of sideline.

Table 1. The most important technical specifications of the Taylor Hobson Form Talysurf instrument.

Property	Information
Instrument and operational principle	Taylor Hobson Form Talysurf Ser. 2, Type 112/2815-02, inductive
Measurement tips	Diamond tip, radius 0.002 mm, Spherical sapphire tip, radius 0.397 mm.
Measurement forces	1.0 mN (using diamond tip), 15–20 mN (using sapphire tip)
Surface texture parameters	R3y, R3z, Ra, Rc, Rda, Rdc, Rdq, RHSC, Rku, Rln, RLo, RIq, Rmr, Rmr(c), Rp, RPc, Rq, RS, Rsk, RSm, Rt, Rv, RVo, Rz, Rz(JIS). In addition, a series of waviness parameters.
Longest measurement length	120 mm
Maximum height of artefact	700 mm, maximum width in 3D measurement is 50 mm
Largest allowed deviation	28 mm (120 mm arm)
Measurement speed	1 mm/s
Resolution	0.0006 $\mu$ m
Lowest uncertainty	$Q[10 \text{ nm}, 0.02 P]$ where $P$ is the deviation from flatness

# Optical measurement of surface microstructures

Ville Heikkinen, Research Scientist  
Tel. +358 50 415 5980  
[ville.heikkinen@vtt.fi](mailto:ville.heikkinen@vtt.fi)

Björn Hemming, Senior Scientist  
Tel. +358 50 773 5744  
[bjorn.hemming@vtt.fi](mailto:bjorn.hemming@vtt.fi)

VTT MIKES  
Tekniikantie 1, FI-02150 Espoo, Finland  
Tel. +358 20 722 111

Micro to millimetre range structures can be measured at VTT MIKES using scanning white light interference microscope (SWLI).

The SWLI has sub-nm vertical and  $\mu\text{m}$  level horizontal resolution. It can measure square mm areas in a single scan. Benefit of SWLI compared to other instruments with similar vertical resolution include large measurement area ability to measure high steps and ability to measure overlapping surfaces inside of transparent structures. See table 1 for more properties of the instrument.

Real life measurement uncertainty is case dependent and depends on measurement environment, properties of instrument and properties of measured sample. At VTT MIKES, we take care that the sample is clean, sample temperature is known and the sample is well attached and properly aligned. Measurements are done traceably under consistent conditions and results are well documented.

## Examples of potential measurement objects:

- Bearings, contact surfaces, surface topography and wear
- Semiconductors and MEMS
- Medical instruments and implants
- Optical components
- Precision machined components

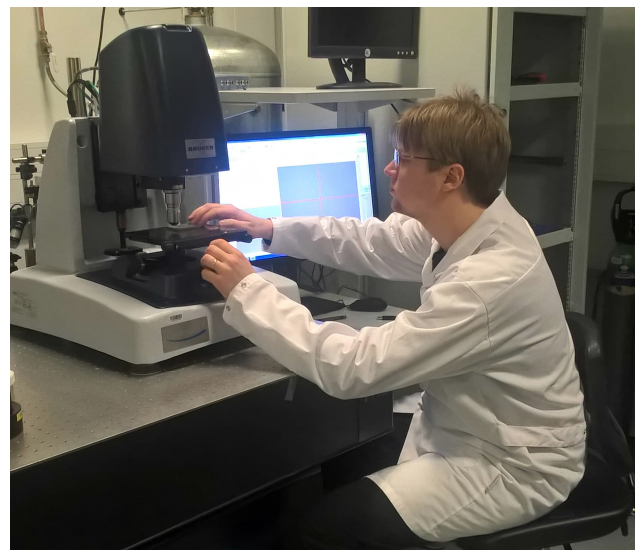


Figure 1. Bruker ContourGT-K scanning white light interferometer.

## We do different measurements using the SWLI

- Different type of objects
  - surface shape measurements
  - x,y,z dimensions of details on a surface
  - film thickness measurement, layer separation
  - surface roughness (2D and 3D ISO roughness parameters), flatness, deviation from a shape
- Calibration of different instruments
- Calibration of reference artefacts
  - step heights, air gap artefacts, film thickness artefacts

## Optical measurements of surface microstructures

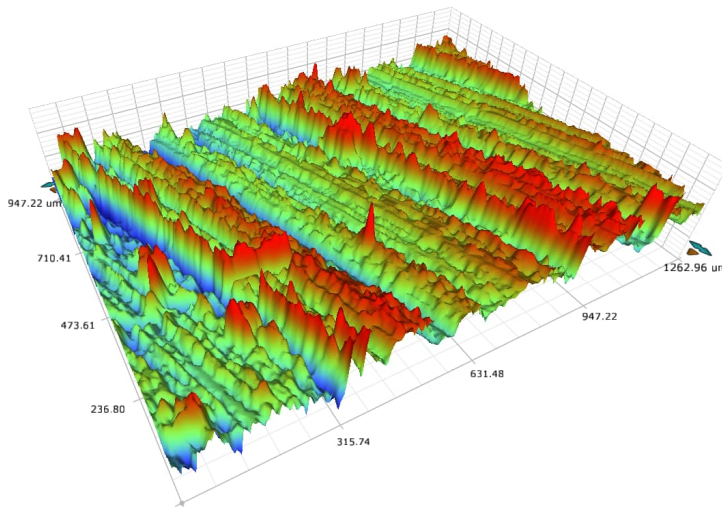


Figure 2. Measurement of machined aluminium surface

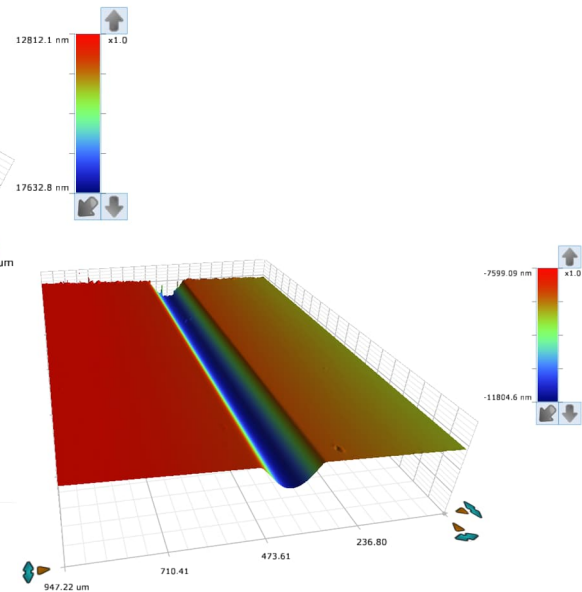


Figure 3. Measurement of a groove on a glass surface.

## Optimal measurement condition

SWLI is in underground measurement room with ( $20 \pm 0.1$ ) °C temperature. Most heat sources in the room have been eliminated by venting warm air out.

## Traceability

SWLI is traceable to the SI-metre through VTT MIKES's own transfer standards such as step height standards, gauge blocks and laser interferometer.

Table 1. Properties of SWLI

Property	Information
Optical x-y resolution	3.8 – 0.7 $\mu\text{m}$
Pixel size	7.2 – 0.2 $\mu\text{m}$
Vertical resolution	< 0.1 nm
Step height measurement:	
• repeatability	< 0.1 %
• accuracy	< 0.75 %
Sample reflectivity:	0.05 % – 100 %
Maximum surface tilt (smooth samples):	3° (2.5 $\times$ objective), 18.9° (20 $\times$ objective)
Magnifications	2.5 $\times$ and 20 $\times$ objectives, 0.55 $\times$ , 1 $\times$ and 2 $\times$ zoom lenses
Measurement area (X $\times$ Y $\times$ Z mm <sup>3</sup> ):	Measurement area (X $\times$ Y $\times$ Z mm <sup>3</sup> ):
smallest magnification	3.5 $\times$ 4.6 $\times$ 3.5
largest magnification	0.4 $\times$ 0.6 $\times$ 3.5
Measurement area in pixels	640 $\times$ 480
Programs	Vision64 Analysis Software, MountainsMap, MatLab
Maximum size of measured object	10 cm high $\times$ 20 cm wide, one dimension can be longer
Ability to measure overlapping surfaces	2 surfaces in single measurement Maximum depth is dependent on refractive index, geometry and magnification, e.g. it is possible to measure through 0.3 mm thick glass. 7 mm maximum depth limited by working distance.

# Measurements of accurate inner and outer dimensions

Juho Kukkohovi, Senior Research Technician  
Tel. +358 50 348 4200  
[juho.kukkohovi@vtt.fi](mailto:juho.kukkohovi@vtt.fi)

Jarkko Unkuri, Research Scientist  
Tel. +358 40 410 5506  
[jarkko.unkuri@vtt.fi](mailto:jarkko.unkuri@vtt.fi)

VTT MIKES, Tekniikantie 1  
FI-02150 Espoo, Finland  
Tel. +358 20 722 111

## Measurements using SIP length measuring machine

Precise measurements of inner and outer diameters are performed using MAHR length measuring machine either by using its own scale or by referencing to a standard of equal length (Figure 2). In the measurement, a contact is made using a ceramic spherical measuring probe, a flat tip or in inner measurements a lever probe. If the measurement depth in inner measurements is over 15 mm, special hook-shaped jaws are used. The measuring force can be tuned between 0.3...11 N. By measuring with several different forces, the deformations due to the measuring forces can be eliminated from calculations and the result given at so-called zero-force.

This is essential when the reference and the artefact under calibration are made of different materials or have different shapes.

Measurements are performed in a well-controlled laboratory room at temperature  $+20\text{ °C} \pm 0.1\text{ °C}$ . Different types of heat sources are eliminated by using vent pipes, heat shields, and when necessary with a separate laminar flow. In addition to the measurement length, the measurement uncertainty depends on the measured artefact (shape and surface texture), on measuring instrument, measurement conditions, and on the method used.

In addition to diameter measurements, the MAHR length measuring machine is used for thread measurements and tolerance comparisons. The inner threads are measured using spherical probes and in outer thread measurements, three-wire method is used.



Figure 1. Measurement using MAHR length measuring machine.

## Measurements supplementing diameter measurements

In order to get a precise picture of the features of an axially symmetrical artefact that is under measurement, one should also measure its roundness, surface roughness and straightness of sides using appropriate instruments.

## Traceability

Measurements made using the SIP length measuring machine are traceable to corresponding transfer standards that are calibrated at VTT MIKES. The linear scale is calibrated using a laser interferometer, the reference gauge blocks are calibrated interferometrically, and the temperature sensors are calibrated in temperature baths against reference Pt25 thermocouples.



Figure 2. Mounting side by side the artefact under calibration and the reference in a comparison measurement.

Table 1. Measurement uncertainties achievable in diameter measurements.

Measurement artefact	Measurement uncertainty ( $k=2$ )
Thread plug 0 – 550 mm	$Q[0.2 \mu\text{m}, 0.87\text{E-}6 L]$
Ring gauge 1 – 500 mm	$Q[0.2 \mu\text{m}, 0.87\text{E-}6 L]$
Sphere 0.2 mm ... 200 mm	$Q[0.15 \mu\text{m}, 0.7\text{E-}6 L]$
	$L$ nominal diameter

# Coordinate measurement

Linus Teir, Research Scientist  
Tel. +358 40 655 4829  
[linus.teir@vtt.fi](mailto:linus.teir@vtt.fi)

Ville Byman, Research Scientist  
Puh. +358 50 386 9327  
[ville.byman@vtt.fi](mailto:ville.byman@vtt.fi)

VTT MIKES, Tekniikantie 1  
FI-02150 Espoo, Finland  
Tel. +358 20 722 111

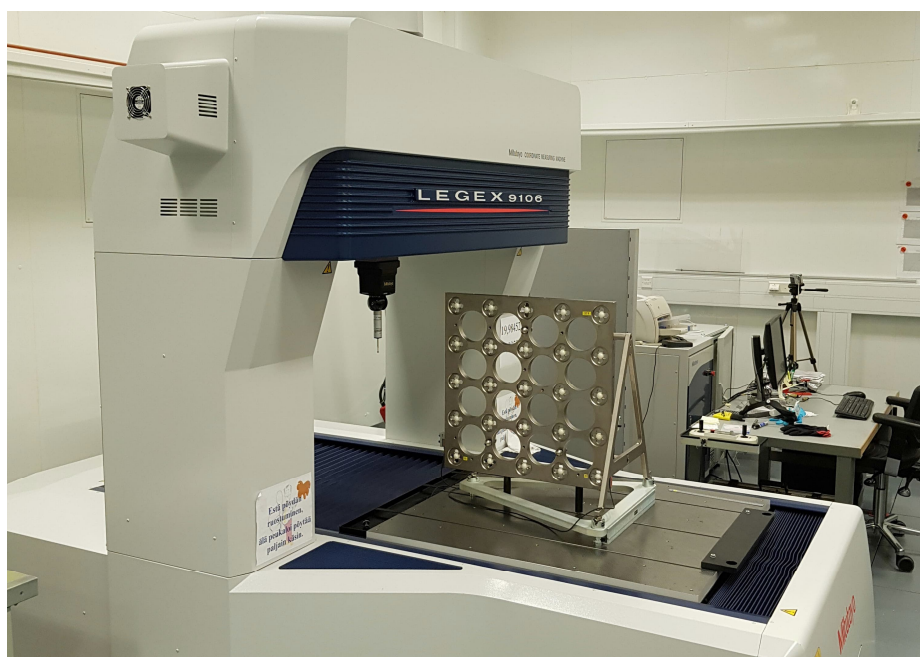
The coordinate measuring services at VTT MIKES include measurements with an optical coordinate measuring machine and with a high-accuracy industrial size contact probe coordinate measuring machine.

## Contacting coordinate measurement

The basic properties of VTT MIKES coordinate measuring machine are accuracy, flexibility, speed, and automatic calculation of results.

The VTT MIKES 3D coordinate measuring machine is a Mitutoyo Legex 9106 with portal structure (Figure 1). Further information on this machine can be found in Table 1. The true measurement uncertainty is always case-specific and depends on the environmental conditions, on the machine, and on the properties of the work piece. We pay special attention in our working on surface cleanliness, temperature, mounting (Figure 2), alignment, measuring system, and on the documentation of results.

Figure 1. Mitutoyo Legex coordinate measuring machine.



The coordinate measuring machine is used for:

- custom measurements of 3D-workpieces (figure 3) and difficult shapes
  - scanning
  - digitizing point clouds
- various calibration of measurement devices
  - rulers, surface plates, gauges, cones, squares
- calibration of transfer standards for coordinate machines
  - step gauges, ball cubes.

## Optimal measurement conditions underground

The coordinate measuring machine is located in a large volume underground laboratory room held at  $(20 \pm 0.2) ^\circ\text{C}$  constant temperature. Most of the heat sources in the laboratory are eliminated using vent pipes. Moreover, the room is equipped with a 1000-kg load lifter on rails and a lift with 4000 kg maximum load capacity can be used to haul the goods into the laboratory.

## Traceability

In commissioning, various laser and gauge block measurement were carried out on the coordinate measuring machine. Furthermore, the machine is regularly calibrated using our own measurement standards: step gauges, ball plates, and a laser interferometer. The measurement uncertainty and traceability are verified in each case separately using so-called substitute method, i.e. results are corrected using the results of a calibrated standard.

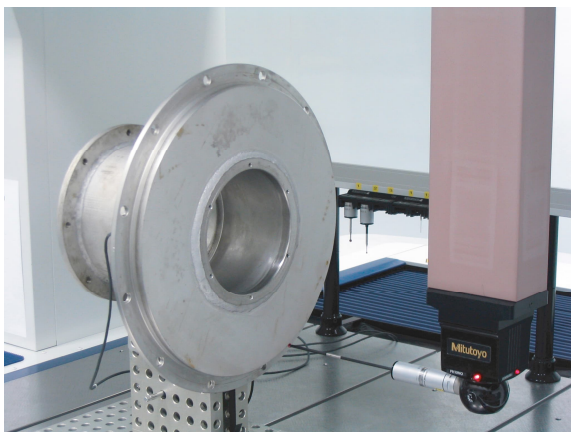


Figure 3. A typical artefact that can be measured using a coordinate measuring machine.



Figure 2. The proper mounting of work pieces is important.

Table 1. The main properties of the coordinate measuring machine.

Property	Data
Performance checked according to ISO 10360-2:	
• maximum error in length measurements	MPE <sub>L</sub> = $(0.35 + L / 1000) \mu\text{m}$ , L = mm
• maximum 3D contact deviation	MPE <sub>P</sub> = 0.35 $\mu\text{m}$
• maximum error in scanning measurement	MPE <sub>thp</sub> = 1.4 $\mu\text{m}$
Error of laser scanner head	1.8 $\mu\text{m}$
Scales	Mitutoyo Zerodur scales with floating mounting, resolution 0.01 $\mu\text{m}$ .
Travelling length	X-910 mm, Y-1010 mm and Z-610 mm
Contact probe	Renishaw indexing head PH10MQ Renishaw SP25M contact and scanning probe
Measuring force	0.03 N...0.09 N
Software	Mitutoyo COSMOS software <ul style="list-style-type: none"> <li>• Geopak-Win geometry program</li> <li>• Statpak-Win geostatistical analysis for quality control</li> <li>• Scanpak-Win form measurement</li> <li>• 3Dtol-Win/ MCAD300 comparison with CAD models and importing CAD data</li> </ul>
Laser head	SurfaceMeasure 201FS
Max. workpiece mass	800 kg
Diameter of probes	0.5 mm...30 mm

# Optical coordinate measuring – vision measuring

Ville Byman, Research Scientist  
Tel. +358 50 386 9327  
[ville.byman@vtt.fi](mailto:ville.byman@vtt.fi)

VTT MIKES  
Tekniikantie 1, FI-02150 Espoo, Finland  
Tel. +358 20 722 111

The manufacturing tolerances of modern products and the aim for high quality require ability to make precise measurement of dimensional measurands on small artefacts of complicated shapes. The use of vision measuring machines and machine vision is well established in non-contact high-precision measurement.

VTT MIKES have a Mitutoyo Quickvision Hyper QV-350 vision measuring machine (optical CMM or video measuring machine) that is equipped with a CCD-camera as well as with a contact probe. In non-contact optical measurements, the machine takes advantage of the measurement point location detected by the CCD camera and location information from the precise scales attached to mechanical guides.

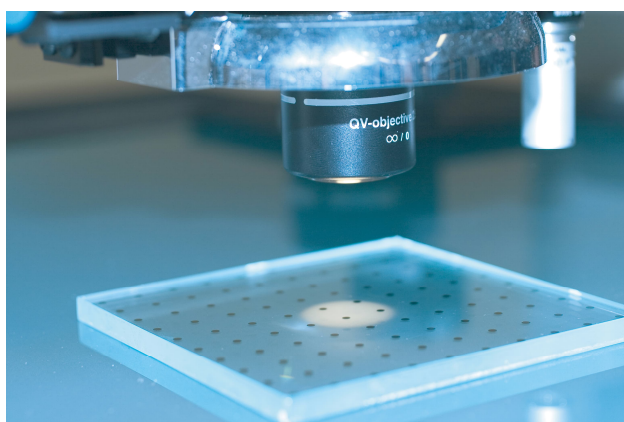


Figure 2. The artefact under study can be illuminated with ring, coaxial or stage light.



Figure 1. VTT MIKES vision co-ordinate measuring machine.

The machine is computer-controlled and measurements are fully automated. The machine is capable to measure length, diameter, angle, straightness, flatness, parallelism, and roundness.

The machine is especially suitable for measurements of circuit boards, thin-walled fragile plastic and metallic artefacts, and other artefacts that are inconvenient or impossible to measure with techniques using contact probes.

The artefact under study can be illuminated with ring, coaxial or stage light. There are four controllable segments in the ring light and its height can be adjusted.

VTT MIKES provides precise optical and contact dimensional measurements tailored according to customers' needs. Depending on the work order, a calibration certificate or a field log is provided.

Table 1. Properties of the vision measuring machine.

Property	Data
Measuring volume	350 mm x 350 mm x 150 mm
Size of the bench	490 mm x 550 mm
Max. workpiece mass	15 kg
Lowest measurement uncertainty ( $k=2$ ), optical mode	$U1XY = (0.8 + 2 L/1000) \mu m^*$ $U2XY = (1.4 + 3 L/1000) \mu m^*$ $U1Z = (3 + 2 L/1000) \mu m^*$
Lowest measurement uncertainty ( $k=2$ ), contact mode	$U1XY = (1.8 + 2 L/1000) \mu m^*$
Max. speed (rapid travel)	100 mm/s
Maximum acceleration	490 mm/s <sup>2</sup>

\* L is length in mm. U1 uncertainty along one axel, U2 along two axels.

# Inspection of optical 3D coordinate measuring systems

Linus Teir, Research Scientist  
Tel. +358 40 655 4829  
[linus.teir@vtt.fi](mailto:linus.teir@vtt.fi)

Ville Byman, Research Scientist  
Tel. +358 50 386 9327  
[ville.byman@vtt.fi](mailto:ville.byman@vtt.fi)

VTT MIKES, Tekniikantie 1,  
FI-02150 Espoo,  
Finland

## Optical 3D coordinate measuring systems in industry

Optical 3D coordinate measuring systems can measure almost anything without contact, from micrometre-scale surface roughness of small objects to large structures like buildings and bridges. VTT MIKES offers inspection and calibration services for these areas, but here we focus on measurements for the manufacturing industry.

Optical 3D measurement has several advantages over tactile measurements with a coordinate measuring machine. For example, a fringe projection device can measure millions of points on an object at high speed and create a 3D model (Figures 1–2). However, compared to traditional tactile measurements, optical 3D measurements face challenges such as lower accuracy and insufficient awareness of this accuracy. The cornerstone of quality inspection is understanding the measurement accuracy of production. If the accuracy, or measurement uncertainty, is unknown, the usefulness and value of the measurement results are questionable.

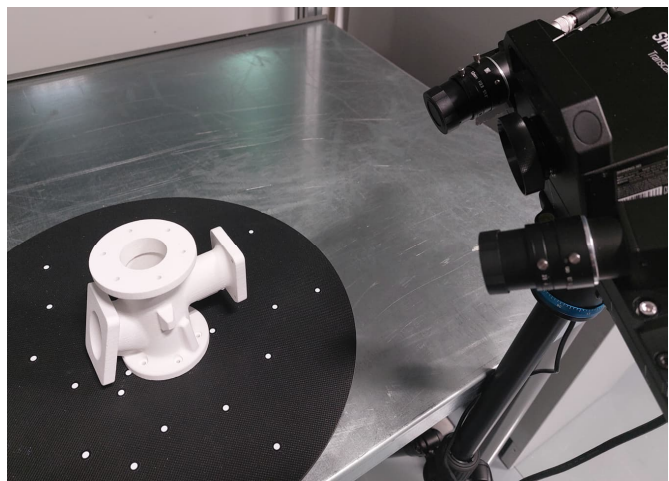


Figure 1. On the left, the object to be measured on a rotary table, and on the right, a 3D scanner based on fringe projection.

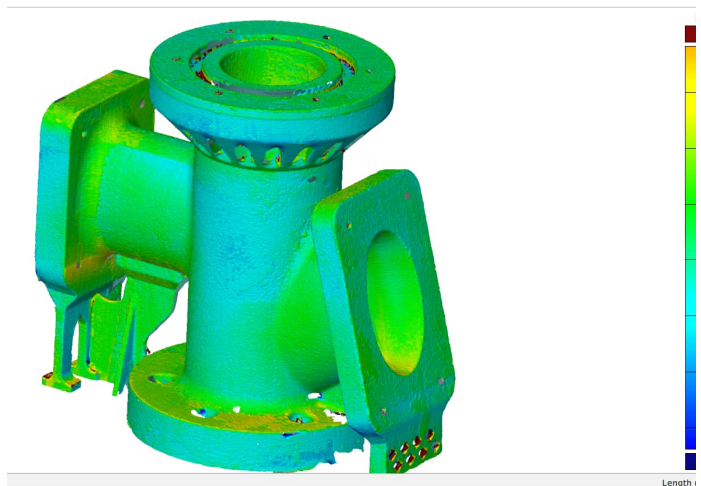


Figure 2. Scanned 3D data and comparison with CAD model.

## Solution

Standard ISO 10360-13 has been established for the inspection of optical 3D measuring instruments. It is essential to use different test pieces for the inspection of the instrument than those used by the vendor's representative to adjust or tune the instrument.

The solution offered by VTT MIKES is based on this standard and the ball bar developed by VTT MIKES. The ball bar (Figure 3) also includes a resolution check piece (Figure 4) with steps in decreasing increments.

The ball bar is placed in the measuring volume and the measurement is repeated by placing it in several positions. In a situation where the measuring device rotates around the bar in several orientations, a vertical, horizontal and diagonal position is sufficient for the bar.

The results reported are the deviations of the distances of the centres of the spheres from the reference values (Figure 5), the diameter error measured from the sphere and the form error. The results of the resolution check piece show how small details can be reliably registered by the instrument.

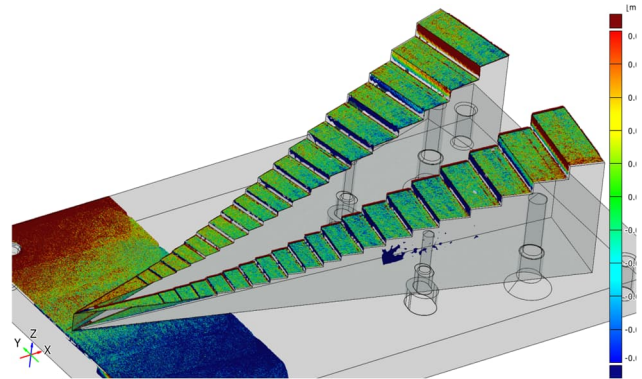


Figure 4. Scanned resolution check piece.

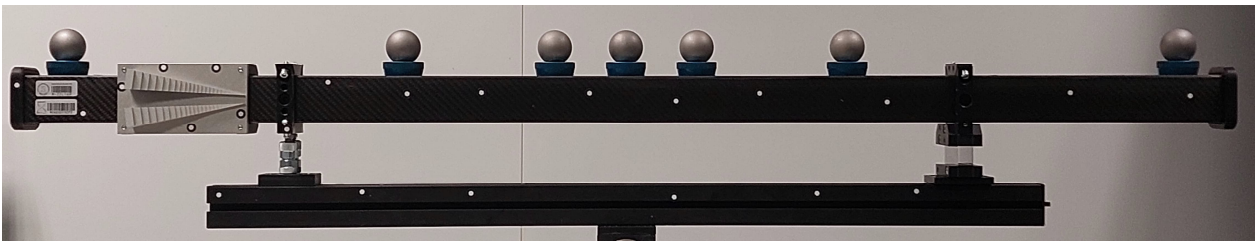


Figure 3. A ball bar from which deviations of ball distances from the reference values are checked and a resolution check piece.

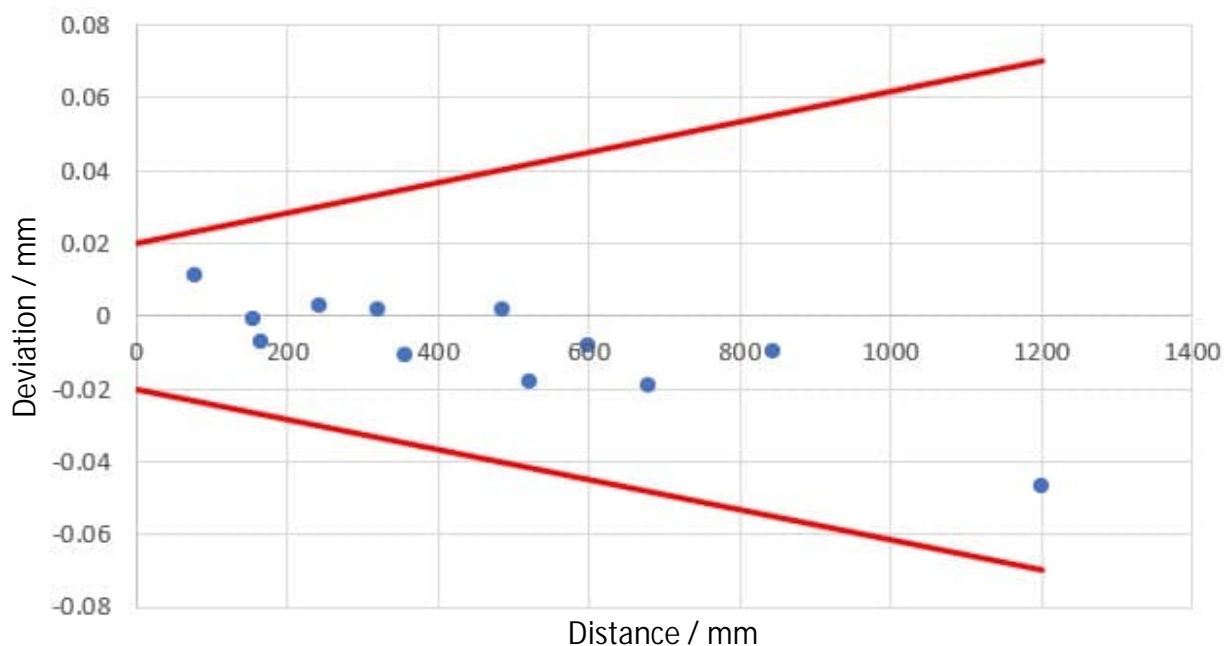


Figure 5. The calibration result clearly indicates the measurement capability, which can be compared with the specification of the instrument.

# High-accuracy line scale calibrations

Ville Byman, Research Scientist  
tel. +358 50 386 9327  
[ville.byman@vtt.fi](mailto:ville.byman@vtt.fi)

Antti Lassila, Research Team Leader  
tel. +358 40 767 8584  
[antti.lassila@vtt.fi](mailto:antti.lassila@vtt.fi)

VTT MIKES  
Tekniikantie 1, FI-02150 Espoo, Finland  
Puh. +358 20 722 111

## Line scale interferometer

VTT MIKES interferometer for high accuracy calibration of line scales provides highest class measurement accuracy up to 1.12 m. The instrument is situated in air-conditioned laboratory: air temperature is  $20\text{ }^{\circ}\text{C} \pm 0.05\text{ }^{\circ}\text{C}$  and relative humidity is  $45 \pm 5\text{ }%$ .

The instrument measures line distances automatically utilizing a special interferometer and a CCD camera with microscope. The line scale is positioned under the microscope with support from Airy points to keep bending in minimum. The refractive index of air is determined with air temperature, pressure and humidity meters and an updated Edlen formula. Thermal expansion correction is made using material temperature data from 4 Pt-100 sensors.

The line distance to be calibrated can vary from  $10\text{ }\mu\text{m}$  to 1.12 m. The instrument is suitable for metallic line scales, for glass microscope graticules and for high accuracy LTEC quartz or Zerodur scales.

Automated and dynamic measurement method enables measurement of all line distances on the scale with economic cost. When using line scale as transfer standard of meter it's good to understand that also line scales suffer from nonlinearity i.e. the only position of calibrated lines is well known.

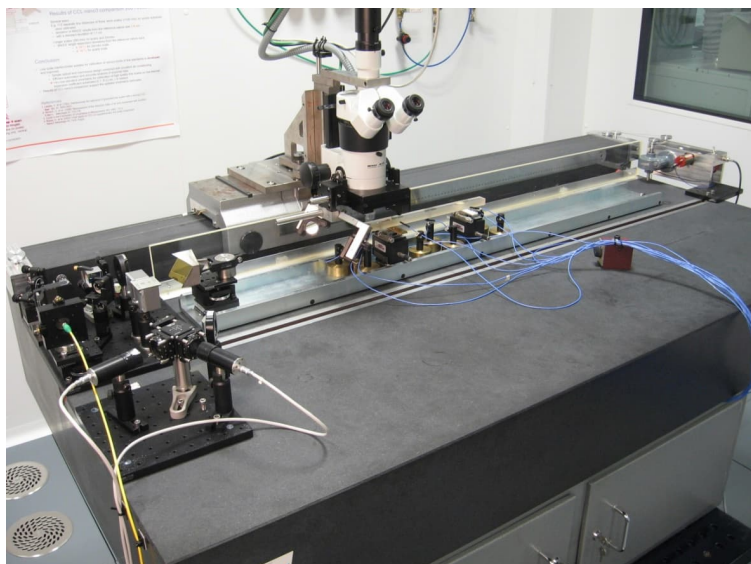


Figure 1. VTT MIKES line scale interferometer.

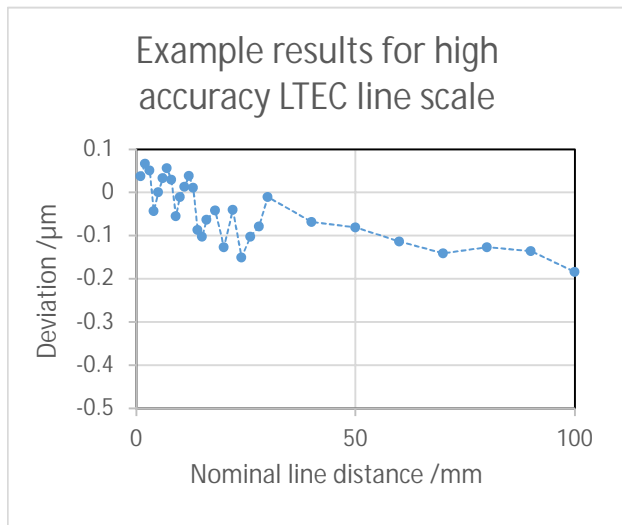


Figure 2. Results of a high quality LTEC line scale reveals nonlinear error of the intermediate line distances. Note area from 0 to 25 mm with denser calibration points.

## Calibration service and uncertainty

Calibration assignment is started by agreeing nominal line distances to be calibrated, location and width of measurement area and targeted uncertainty level. By repeating measurement in different locations and positions it's possible to reduce some of the measurement errors e.g. related to Abbe error and refractive index of air.

## Traceability

The vacuum wavelength of the laser used in line scale interferometer is calibrated against national reference standard iodine stabilized He-Ne laser. Also, temperature, pressure and humidity meters are calibrated against VTT MIKES references.

The correct operation of the line scale interferometer is ensured by regular participation to EURAMET TC-Length of CCL key comparisons.

Best measurement uncertainty is reached with LTEC line scale with excellent graduation mark quality, i.e. line edge straightness and width are regular. Also guidelines to show the position of the measurement area will improve reproducibility of the measurements. If small uncertainty is sought also the flatness deviation of the line scale surface should be excellent and at least better than 50 µm.

Customer may choose economic basic calibration or high accuracy calibration whatever he/she needs most. Also amount of line distance to be measured has effect to service price. However, basic price includes at least 50 line distances.

In table 1 there are uncertainties for different services.

### References:

Lassila, A. (2012). MIKES fibre-coupled differential dynamic line scale interferometer. *Measurement Science and Technology* **23**(9), [094011].  
<https://doi.org/10.1088/0957-0233/23/9/094011>

Table 1. Uncertainties in line scale calibrations.

Standard	Range	Expanded uncertainty ( $k=2$ )*
Regular line scales, basic calibration	10 µm ... 1.12 m	0.2...0.5 µm
Accurate lines scale, better accuracy calibration	10 µm ... 1.12 m	0.05...0.15 µm
High accuracy line scales, best accuracy calibration	10 µm ... 1.12 m	$Q[6.2 \text{ nm}, 82E-09 L]$ **

$L$  = Nominal length

\* Uncertainty is often larger due to uncertainty caused by properties of the device under calibration

\*\*  $Q[x; y] = (x^2 + y^2)^{1/2}$

# Accurate calibration of step gauges

Ville Byman, Research Scientist  
tel. +358 50 386 9327  
[ville.byman@vtt.fi](mailto:ville.byman@vtt.fi)

Antti Lassila, Research Team Leader  
tel. +358 40 767 8584  
[antti.lassila@vtt.fi](mailto:antti.lassila@vtt.fi)

VTT MIKES  
Tekniikantie 1, FI-02150 Espoo, Finland  
Puh. +358 20 722 111

## Step gauge interferometer

VTT MIKES purposed built step gauge interferometer enables calibration at state of art accuracy up to 2 m length (figure 1). The instrument is situated in air-conditioned laboratory: air temperature is  $20\text{ }^{\circ}\text{C} \pm 0,05\text{ }^{\circ}\text{C}$  and relative humidity is  $(45 \pm 5)\%$ .

The interferometer measures the distances between step gauge surfaces automatically using double pass interferometer and purpose-built measuring head. The step gauge is adjusted accurately to correct position and direction with aid of an integrated 3d position sensor. The refractive index of air is determined

with air temperature, pressure and humidity meters and an updated Edlen formula. Thermal expansion correction is made using material temperature data from 4 Pt-100 sensors.

The instrument is suitable to many kinds of step gauges e.g. Koba and Mitutoyo type step gauges can be calibrated with it. Automatic measurement method with high quality laboratory conditions enables economic high accuracy calibration.



Figure 1. VTT MIKES interferometer for calibration of step gauges.

## Calibration service and uncertainty

Calibration assignment is started by agreeing targeted uncertainty level. By repeating measurement in different locations and positions it's possible to reduce some of the measurement errors e.g. related to Abbe error and refractive index of air.

Customer may choose economic basic calibration or high accuracy calibration whatever he/she needs most.

Table 1 shows uncertainties for different services.

Table 1. Measurement uncertainty.

Service	Range	Uncertainty ( $k=2$ )*
Economic basic calibration	10 mm... 2 m	0.3 $\mu\text{m/m}$
Accurate calibration	10 mm ...2 m	0.15 $\mu\text{m/m}$
High-accuracy calibration	10 mm ... 2 m	$Q[64 \text{ nm}, 88\text{E-}9 L]**$

$L$  = Nominal length

\* Uncertainty is often larger due to uncertainty caused by properties of the device under calibration

\*\*  $Q[x; y] = (x^2 + y^2)^{1/2}$

### References:

Byman, V., Jaakkola, T., Palosuo, I., & Lassila, A. (2018). High accuracy step gauge interferometer. *Measurement Science and Technology* **29**(5), [054003]. <https://doi.org/10.1088/1361-6501/aaad32>

Coveney, T., et al., Calibration of 1-D CMM artefacts: step gauges (EURAMET.L-K5.2016) et al, 2020, *Metrologia* **57** 04002. <https://doi.org/10.1088/0026-1394/57/1A/04002>

## Traceability

The vacuum wavelength of the laser used in the step interferometer is calibrated against national reference standard iodine stabilized He-Ne laser. Also, temperature, pressure and humidity meters are calibrated against VTT MIKES references.

The correct operation of the step gauge interferometer is ensured by regular participation to EURAMET TC-Length of CCL key comparisons.

# Calibration of rulers, tapes and distance meters

Jarkko Unkuri, Research Scientist  
Tel. +358 40 410 5506  
jarkko.unkuri@vtt.fi

Antti Lassila, Research Team Leader  
Tel. +358 40 767 8584  
antti.lassila@vtt.fi

VTT MIKES  
Tekniikantie 1, FI-02150 Espoo, Finland  
Tel. +358 20 722 111

## Calibration of rulers, tapes and distance meters

### 30-m measuring rail

VTT MIKES 30-m measuring rail (Figure 2) offers good possibilities for calibration of precise length measuring devices. The temperature of the measurement room is kept at  $(20 \pm 0.5) ^\circ\text{C}$  and the relative humidity at  $(45 \pm 5) \%$ . The 30-m rail is realised using a high-quality linear motion guide and a movable measurement carriage. A microscope, a CCD camera and a monitor used in line scale measurements are mounted on the carriage. The position of the microscope is measured using a laser interferometer.

The temperature stability of the measurement room and precise gauges & sensors allow precise thermal expansion and refractive index of air compensation. The rail is suitable for calibration of various length standards. The calibrated devices can be physical artefacts like tapes and machinist scales or e.g. optical distance meters. Tapes and other flexible length standards are tensioned using a standardized force, a force given by the manufacturer or a force separately agreed with customer. Most commonly a 50-Nm force of is used for tapes.

For thermal expansion compensation, a measured temperature and a coefficient given by the manufacturer or by the customer are used.



Figure 1. 30 interferometric bench.

## Traceability

The wavelengths of the lasers used in the 30-m measuring rail are calibrated using national measurement standard of length, iodine-stabilized He-Ne laser. The temperature, pressure, and humidity sensors used in the measuring rail are calibrated at VTT MIKES.

Table 1. Line scales, measuring ranges and measurement uncertainties.

Device	Measuring range	Uncertainty* ( $k=2$ )
Tapes, wires	0.001 m ... 30 m, (60, 90 ...) m	$Q[35; 2 L] \mu\text{m}^{**}$
Machinist scales	0.001 m ... 5 m	10 $\mu\text{m}$
Circometer	0.1 m ... 9.55 m (diameter)	$Q[7; 2 D] \mu\text{m}^{**}$
Plumb tapes	1 m ... 30, (60, 90) m	$Q[250; 5 L] \text{mm}^{**}$
Other devices	0 m ... 30 m	(case dependent)

$L, D$  = measured length or corresponding diameter in meters

\* The uncertainty of calibration is often larger than the aforementioned uncertainties due to the uncertainty resulting from the device to be calibrated.

\*\* Calculation of uncertainty  $Q[x; y] = (x^2 + y^2)^{1/2}$

# Interferometric measurement of flatness and form

Björn Hemming, Senior Scientist  
Tel. +358 50 773 5744  
[bjorn.hemming@vtt.fi](mailto:bjorn.hemming@vtt.fi)

Ville Byman, Research Scientist  
Tel. +358 50 386 9327  
[ville.byman@vtt.fi](mailto:ville.byman@vtt.fi)

VTT MIKES  
Tekniikantie 1, FI-02150 Espoo, Finland  
Tel. +358 20 722 111

## Flatness

The surface structure and especially the flatness of the surface are important features of various components used in different areas of technology and physics. Examples of these include silicon wafers in semiconductor industry, sealing faces, bearing areas, contact surfaces in contact measurement methods and surfaces of optical flats and lenses used for reflecting and refracting light.

An optical flat is an easy to use transfer standard for flatness. In industry, optical flats are used, e.g. for

flatness measurements of gauge blocks and contact surfaces of micrometre gauges. In these cases, the quality of the surfaces of optical flats is of essential importance for successful measurements of subject surfaces. Moreover, optical flats are used to transfer flatness to interferometers measuring flatness and to other devices inspecting flatness in industry.

VTT MIKES provides aforementioned measurements and metrological traceability with its equipment for flatness and form measurements (Figure 1).



Figure 1. Calibration of an optical flat.

## Measurement method

The measurement device for flatness at VTT MIKES is a Fizeau interferometer that uses a He-Ne laser at wavelength 633nm as a light source. Interference fringes are obtained by adjusting a small angle between the reference plane and the plane to be measured. The shapes of the interference fringes are analysed by using a so-called phase stepping method. As a result, one receives deviations of the plane under inspection from the reference plane (Figure 2). The advantages of the method are speed, precision, and the fact that the entire measurement area is measured at once.

## Traceability

The reference plane of the optical flat used in the interferometer is of high quality: deviations from a perfect plane are less than 20 nm. The reference plane is calculated either by using an absolute three-point method or by comparing it to a liquid plane. Optical flats having different reflection coefficients are available which allows inspections of mirror surfaces as well as glass surfaces.

## Measurement services

The VTT MIKES equipment (Zygo GPI) can be used for surface profile measurements of objects that have diameters below 150 mm, best available measurement precision being 45 nm. A prerequisite for such measurements is that the height variations of the artefact are less than 12  $\mu\text{m}$  and slowly varying. As the method is based on interference of light and thus it is a non-contacting method, it is also applicable for fragile materials. Moreover, it is applicable for very demanding measurement tasks due to its precision.

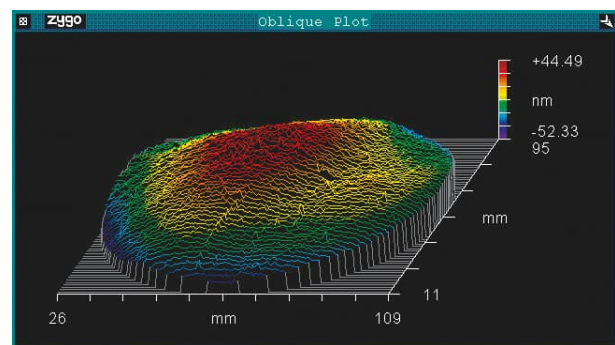


Figure 2. An example of measured surface profile of an optical flat.

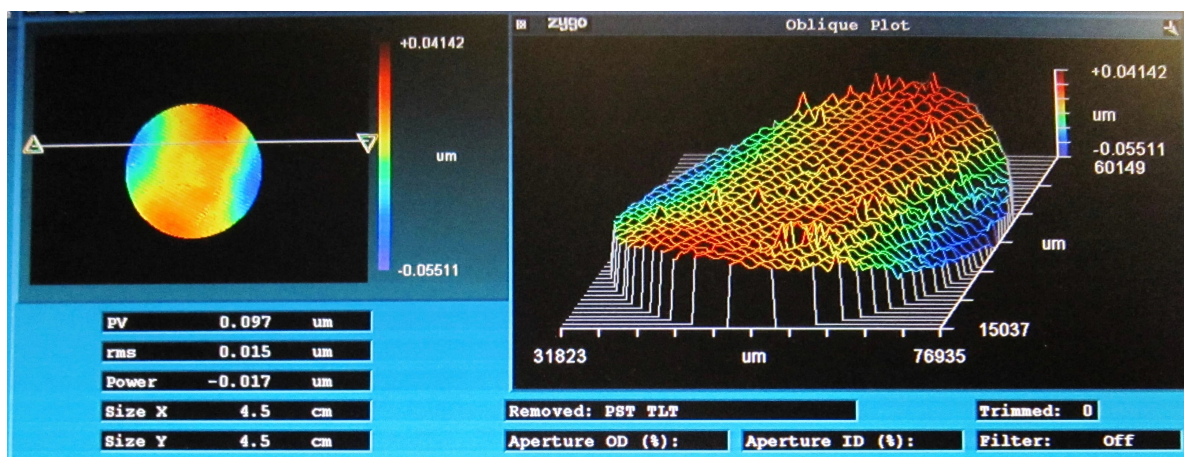


Figure 2. An example of measured surface profile of an optical flat.

# Machine tool measurements

Pasi Laukkanen, Research Engineer  
Tel. +358 50 382 9674  
[pasi.laukkanen@vtt.fi](mailto:pasi.laukkanen@vtt.fi)

Antti Lassila, Research Team Leader  
Tel. +358 40 767 8584  
[antti.lassila@vtt.fi](mailto:antti.lassila@vtt.fi)

VTT MIKES, Tekniikantie 1,  
FI-02150 Espoo, Finland  
Tel. +358 20 722 111

Demands of production and quality systems require knowledge on the precision of machine tools. Different measurements are performed on machine tools during acceptance inspection, in connection with transfers, and when striving for preventive maintenance. VTT MIKES provides its wide experience on dimensional and geometrical measurements, positioning and repeatability accuracy measurements, and measurements on machine-tooled test work pieces.

The competent and experienced personnel of VTT MIKES, modern equipment and continuous development of new measurement methods guarantee customers' precise measurements performed according to standards.

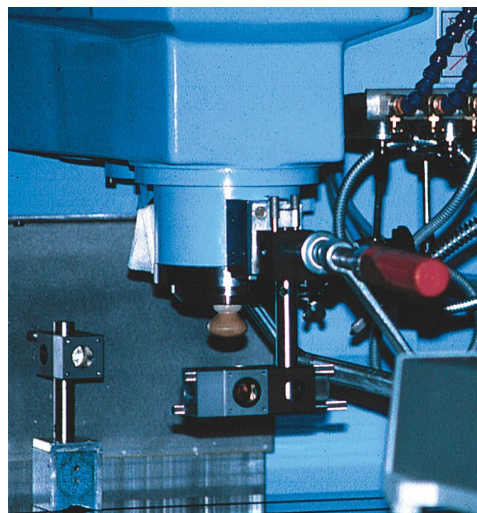


Figure 1. Scale measurement for a machine tool.

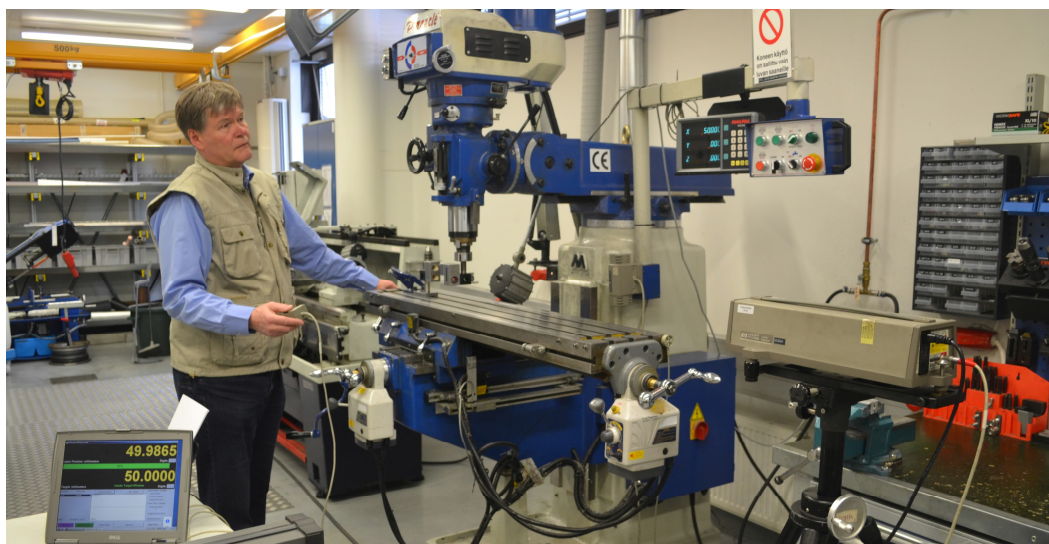


Figure 2. Setup for machine tool measurements.

## Geometrical measurements

Geometrical measurements are used for finding out the form defects in the most important organs of a machine tool and the mutual locations and positions of the organs. VTT MIKES performs geometrical measurements according to ISO and DIN standards. The most important measurements subjects are measurement of spindle runout, the parallelism between the spindle and the machine, perpendicularity measurements, and straightness and perpendicularity measurements of machine movements.

## Accurate positioning and repeatability measurements

Spindle positioning and repeatability measurements reveal errors at different points of the spindle. Errors in spindle movement can be compensated for by giving the compensation values to the control unit memory of the machine tool. The positioning measurement performed using VTT MIKES laser interferometer is a fast and precise way to adjust the spindle movements of a machine (Figure 3); the measurement precision is at its best below 0.001 mm/m.

## Measurement of test workpieces

Machine-tooling tests are used to find out the precision of the machine in true machining circumstances. VTT MIKES geometrical measurements and measurements on work pieces made in machine-tooling tests.

complement each other. The work pieces are measured in a temperature-controlled laboratory room using versatile and modern measurement devices and methods. VTT MIKES have a variety of the most common workshop measurement equipment and a selection of special tools (see Table 1).

## Traceability

All measurement standards used in machine tool measurements are calibrated using similar but more accurate VTT MIKES transfer standards.

Table 1. Devices used in machine tool measurements.

Geometrical, positioning and repeatability measurements:	Measurements of test workpieces
– laser interferometers	– surface structure, form, roundness and length measuring machines
– autocollimators	– inductive sensors
– electronic spirit level	– common workshop measurement devices
– inductive sensors	– coordinate measuring machine
– plumb	
– other devices	

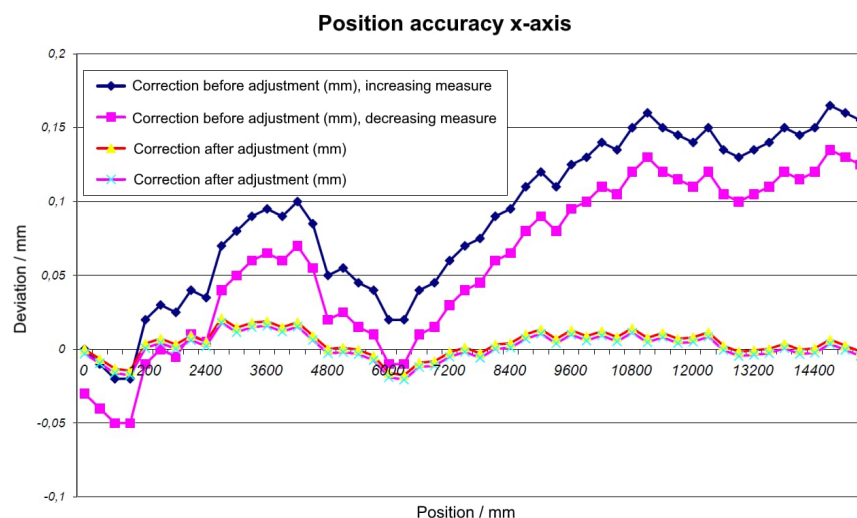


Figure 3. X-axis errors of a broaching machine before laser measurement and adjustment and after.

# Measurement of roundness

Björn Hemming, Senior Scientist  
Tel. +358 50 773 5744g  
[bjorn.hemming@vtt.fi](mailto:bjorn.hemming@vtt.fi)

VTT MIKES  
Tekniikantie 1, FI-02150 Espoo, Finland  
Tel. +358 20 722 111

## Roundness in mechanical engineering industry

Approximately 80 % of machined work pieces have elements with surfaces of revolution. Roundness has an important role for guaranteeing faultless operation of machines and devices. This is even emphasized when reliability, longevity, low operating costs, and friendliness to the environmental are required.

At VTT MIKES, we perform measurements of roundness on ring gauges, screw-plug gauges, slide bearings, metallic packings and hydraulic and pneumatic components. We also measure runout eccentricity, coaxiality, parallelism and straightness (Figure 1).

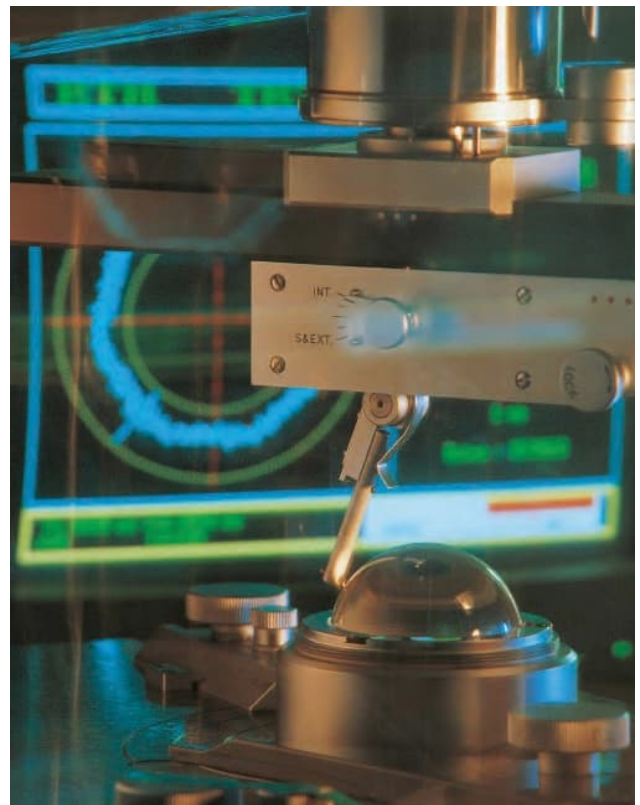


Figure 1. Roundness measurement is an essential part of workshop manufacturing.

## Measurement potential

Roundness is measured either by using a rotating spindle or by using a roundness measurement instrument equipped with a rotating table. Measurements can be performed using several different filters according to the ISO 1101 standard's definition (MZ) or other computing methods (MC, MI, and LS). The use of two alternative machines guarantees the customer that the artefacts can be measured properly and cost effectively. More information on the machines can be found in table 1.

Cylindricity is measured using a machine equipped with a rotating table (Figure 2); with almost the same settings, the following measurement can be performed, also: coaxiality, runout eccentricity, parallelism and straightness. Cylindricity measurements are a part of the calibration of ring gauges and screw-plug gauges.

## Traceability

Traceability to the sensors in both machines comes from magnification standards that are calibrated using VTT MIKES form measurement instrument which in turn gets its traceability from gauge blocks calibrated using an interferometer. The guide bars and shafts in the machines are calibrated using error separation.



Figure 2. Measurement instrument Talyrond 262 for roundness and cylindricity.

Table 1. VTT MIKES roundness and cylindricity measurement instruments.

Model	Rotating part	Maximum height of the artefact mm	Maximum inner/outer diameter of the artefact mm	Maximum mass of the artefact kg	Other	Expanded uncertainty ( $k=2$ )
Talyrond 73HR roundness	spindle	400	175 / 300	100	surface can be discontinuous or asymmetrical	$Q[10 \text{ nm}, 0.01 R]$
Talyrond 262 cylindricity	table	500	– / 350	50	surface can be discontinuous	$Q[0.1 \text{ } \mu\text{m}, 0.001 L]$

$R$  is the deviation from roundness;  $L$  is the height of the cylinder in metres;  $Q[x; y] = (x^2 + y^2)^{1/2}$

# Calibration of microscopes and calibration standards

Virpi Korpelainen, Senior Scientist  
Tel. +358 50 410 5504  
[virpi.korpelainen@vtt.fi](mailto:virpi.korpelainen@vtt.fi)

VTT MIKES  
Tekniikantie 1, FI-02150 Espoo, Finland  
Tel. +358 20 722 111

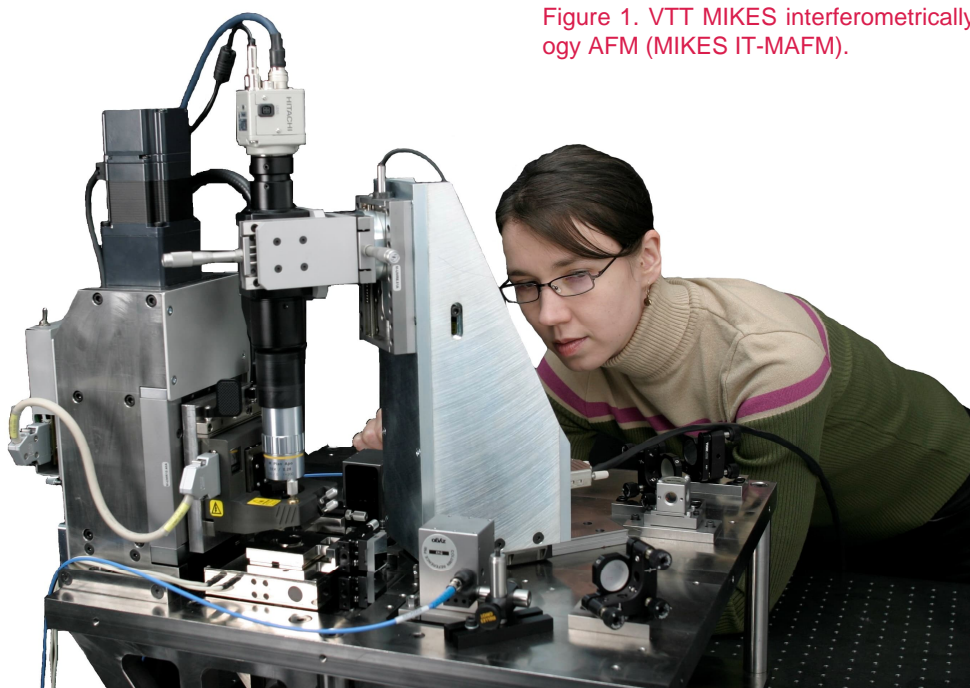
Reliable measurement results in research, manufacture and quality control require knowledge of accuracy of measurement instruments. Calibration is the best way to check the accuracy and stability of the instrument. The calibration can be done with calibrated transfer standards. Official calibration certificate guarantees traceability to the definition of the metre.

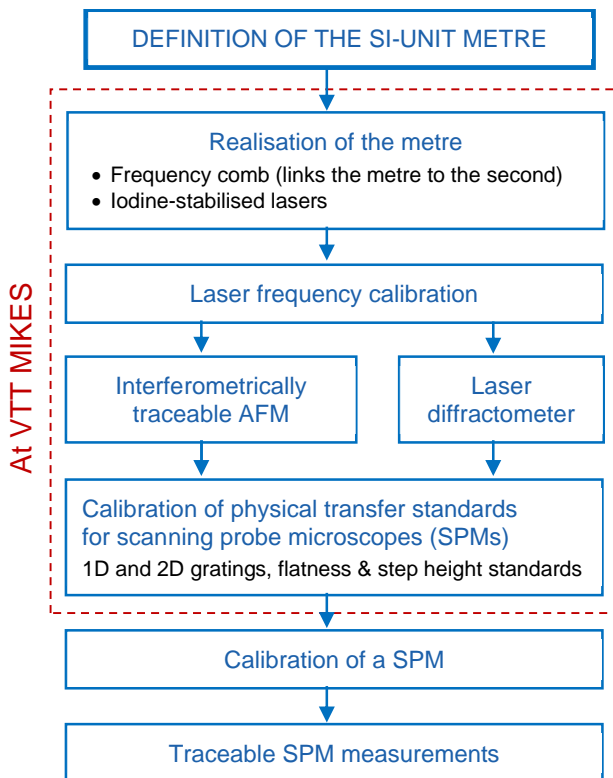
For optical microscopes VTT MIKES provides calibration of high-quality line scales.

Scanning probe microscopes (SPMs) can be calibrated using several kinds of transfer standards [1,2], which can be calibrated at VTT MIKES. 1-D and 2-D gratings are calibrated either by laser diffraction or by metrology atomic force microscope (MAFM). Pitch and orthogonality of the grid can be measured. Step height standards or z scale of 1-D or 2-D gratings can be calibrated.

- [1] Guideline VDI/VDE 2656 Part 1 (Draft): Determination of geometric quantities by Scanning Probe Microscopes - Calibration of Measurement Systems.
- [2] V. Korpelainen and A. Lassila, Calibration of a commercial AFM: traceability for a coordinate system, Meas. Sci. Technol. 18 (2007) 395–403.

Figure 1. VTT MIKES interferometrically traceable metrology AFM (MIKES IT-MAFM).





Calibration itself gives information about the accuracy of the instrument. Accuracy of the measurement can be increased by corrections of the errors detected in the calibration either directly in the measurement software or after the measurement with separate software.

The first step in the calibration is measurement of x and y scale errors by 1-D or 2-D gratings and z scale errors by step height standards. The calibration of the x and y scales gives also information about the linearity of the scales. The linearity of the z scale needs to be checked by several different step height

standards. Orthogonality errors can be detected by 2-D grids. Out-of-plane errors can be measured using a flatness standard. In the most accurate calibrations also some other error types has to be measured and corrected; e.g. orthogonality of z-axis, rotational and other guiding errors. There are also other error sources, which should be taken into account, e.g. tip-sample interactions, vibrations, noise and thermal drift. Calibration period depends on the stability of the device, e.g. microscopes with open loop scanner need calibration before and after each measurement.

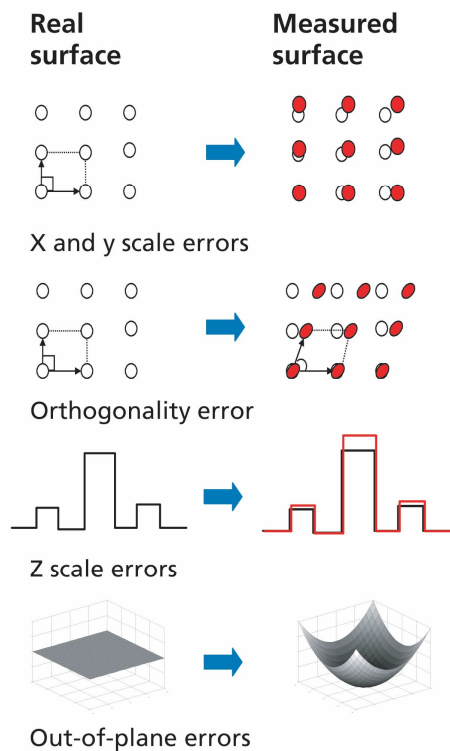


Figure 3. Some error types of SPMs.

Table 1. Calibration services for SPM standards.

		Range	Uncertainty
1-D grid (diffraction measurement)			
	Pitch	300 nm – 10 µm	50 – 100 pm
2-D grid (diffraction measurement)			
	Pitch	300 nm – 10 µm	50 – 100 pm
	Orthogonality		
1-D grid (AFM measurement)			
	Pitch, $p$	100 nm – 10 µm	Q [3.4, 0.2 $p/\mu\text{m}$ ] nm
	Orthogonality		14 mrad
	Step height, $h$	10 nm – 2 µm	Q [2, 0.2 $h/\mu\text{m}$ ] nm
	Flatness	100 µm × 100 µm	5 nm
Step height standard		10 nm – 2 µm	Q [2, 0.2 $h/\mu\text{m}$ ] nm
Flatness standard		100 µm × 100 µm	5 nm

# Calibration of angle and distance measurement functions of laser scanners

Jarkko Unkuri, Research Scientist  
Tel. +358 40 410 5506  
[jarkko.unkuri@vtt.fi](mailto:jarkko.unkuri@vtt.fi)

Antti Lassila, Research Team Leader  
Tel. +358 40 767 8584  
[antti.lassila@vtt.fi](mailto:antti.lassila@vtt.fi)

VTT MIKES, Tekniikantie 1,  
FI-02150 Espoo, Finland  
Tel. +358 20 722 111

## Calibration of a laser scanner with a 30 m measuring rail

The national standard laboratory for length and angle at VTT MIKES has expanded its calibration services to cover calibration of angle and distance measurements of laser scanners.

A laser interferometer on a 30 m measuring rail is used as a reference for calibrating the distance measurement function of a laser scanner.

The angle measurement capability is calibrated using a calibrated two-metre reference scale target and a laser interferometer at three distances in vertical and horizontal positions. The zero-point error is measured with a double-sided target on the rail carriage.

The calibration certificate deviations from the reference dimensions, as shown in Figure 2, and measurement uncertainties are reported.



Figure 1. Calibration of a laser scanner with a 30-metre measuring rail.

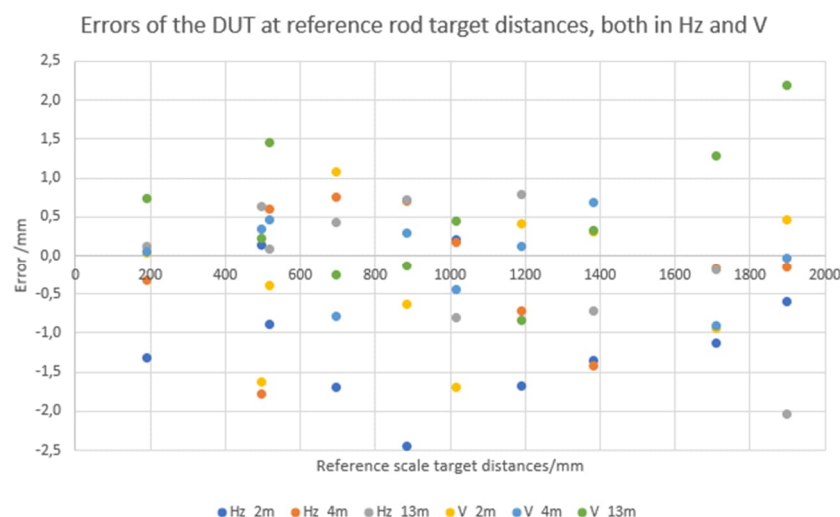


Figure 2. Errors (Hz and V) at different distances of reference scale target.

In order to ensure valid measurement results, ISO 9001/2008 requires that measuring instruments be calibrated or verified either periodically or before use. Standard SFS-EN ISO 10012 "Measurement management systems" requires traceability of the results of measuring instruments.

Traceability is defined as "the property of the result of a measurement or the value of a standard whereby it can be related to stated references, usually national or international standards, through an unbroken chain of comparisons all having stated uncertainties.

Calibration establishes a link between the values obtained with the measuring instrument and the corresponding values obtained with the measurement standards. The calibration certificate also indicates the uncertainty of measurement, a parameter that characterises the dispersion of the values that could reasonably be attributed to the measurand.

# Angle and perpendicularity measurements

Ville Heikkinen, Research Scientist  
Tel. +358 50 415 5980  
[ville.heikkinen@vtt.fi](mailto:ville.heikkinen@vtt.fi)

Antti Lassila, Research Team Leader  
Tel. +358 40 767 8584  
[antti.lassila@vtt.fi](mailto:antti.lassila@vtt.fi)

VTT MIKES, Tekniikantie 1,  
FI-02150 Espoo, Finland  
Tel. +358 20 722 111

Angle measurements are important in all mechanical engineering and construction industry. The significance of angle measurements is increased also in dimensional measurements when dimensions increase. Perpendicularity that is related to right angles and square blocks is an important special case of angle measurement.

The SI-unit for angle is radian (rad) but depending on the branch of industry and the measurement subject other units are commonly used. In mechanical engineering angles are normally expressed in degrees [°], minutes ['] and seconds ["], in geodesy the most commonly used unit is gon [gon] (also referred to as grade). In earth-moving work and for small angles the unit [mm/m] is generally used. The diverse group of units for angle include also the following ways to express the angle: percent [%] and length ratios.

Perpendicularity according to the ISO1101 standard:

- As a result the width  $t$  of tolerance zone is given
- One side is defined as the reference side and only against this side the perpendicularity is determined.

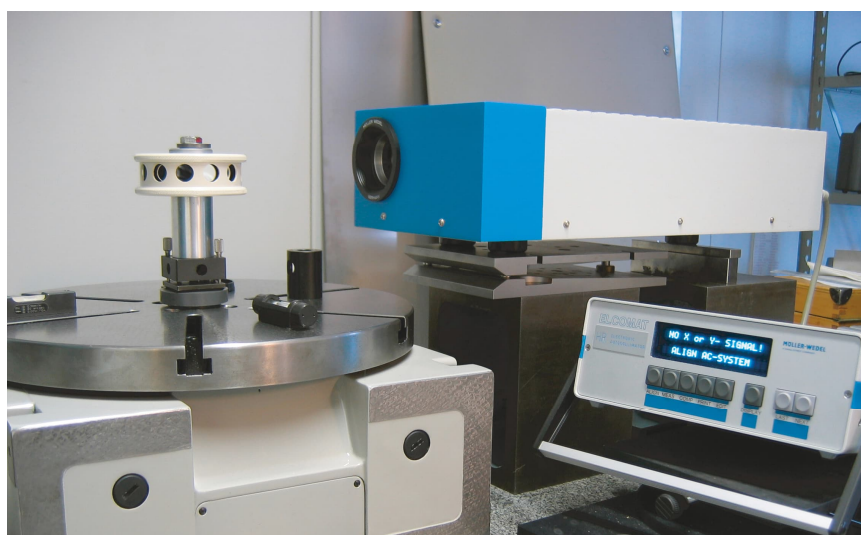
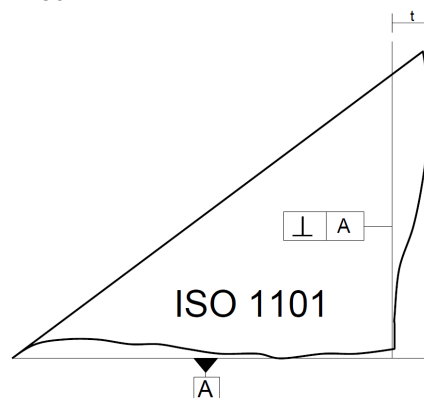


Figure 1. Polygon attached to a rotary table. Errors from the rotary table and the polyhedron can be separated by performing a measurement series using a Moller Wedel HPR autocollimator.

## Instruments for measuring angle

The most typical objects of calibration in mechanical workshops are rotary tables of machine tools and measuring machines, universal bevel protractors, angle blocks, and different kinds of spirit (bubble) levels. Typical angle measurement instruments used in machine installation and in construction engineering are e.g. electronic levels, theodolites, levelling instruments, tacheometers, laser interferometers, autocollimators and polygons.

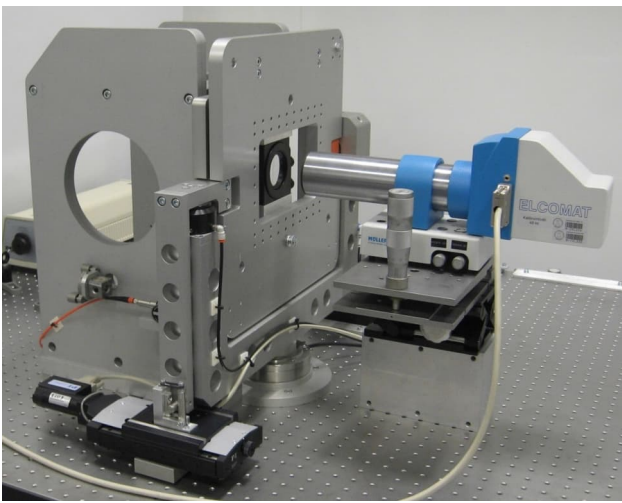


Figure 2. Interferometric 2D small angle generator for calibration of autocollimators developed at VTT MIKES.

## Measurement uncertainty

All measurements are performed in a well-controlled laboratory room at temperature  $+20\text{ °C} \pm 0.1\text{ °C}$ . The achievable measurement uncertainty depends critically on the artefact under calibration and its properties (e.g. form errors and surface roughness)

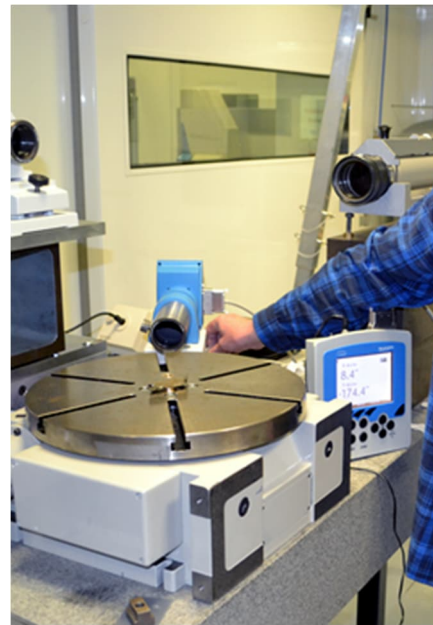


Figure 3. Preparation of angle measurements.

Table 1. Examples of lowest uncertainties for angle measurement instruments.

Instrument	Measuring range	Measurement uncertainty ( $k=2$ )	Limitations
Optical polygons	0° – 360°	0.2"	
Rotary index table	0° – 360°	0.5"	indexing angle $n \times 15^\circ$
Rotary table	0° – 360°	0.2"	
Autocollimator	0° – 1°	0.02"	
Electronic level	0° – 360°	0.2"	
Theodolite	0° – 360°	0.2"	instrument limits the vertical angle
Angle block	0° – 360°	0.2"	
Steel or granite squares	90°	0.5"	maximum length 1 m
Cylinder square	90°	0.5"	maximum length 1 m
Optical right angle	90°	0.5"	

# Calibration of tachymeters

Jarkko Unkuri, Research Scientist  
Tel. +358 40 410 5506  
[jarkko.unkuri@vtt.fi](mailto:jarkko.unkuri@vtt.fi)

Antti Lassila, Research Team Leader  
Tel. +358 40 767 8584  
[antti.lassila@vtt.fi](mailto:antti.lassila@vtt.fi)

VTT MIKES  
Tekniikantie 1, FI-02150 Espoo, Finland  
Tel. +358 20 722 111

*MIKES calibrates angle and distance measurements functions of tachymeters.*

## Calibration of a distance metre in a 30-metre measuring rail

Readings from a distance meter of a tachymeter is compared to readings from a laser interferometer of the 30-metre measuring rail. The measurement axis of the tachymeter and the laser interferometer are aligned to be parallel. The reading of the interferometer is set to zero at the beginning of the measuring rail. The observed reading of the distance meter at the zero point of the interferometer is subtracted from

the readings of the distance meter. In the calibration certificate, the deviations from the references distances and the expanded measurement uncertainty are given for each target point. The target point can be a prism, a reflector tape or a target plate. The measurement uncertainty depends on the scatter of the measurement results and is typically between 0.05 – 0.25 mm for accurate distance meters.



Figure 1. MIKES 30-m measuring rail.

## Calibration of angle measurements by using a rotary table and collimation tubes

The vertical and horizontal scales of a tachymeter are calibrated by using an Eimeldingen rotary table as a reference. The rotary table is calibrated using polygons and collimation tubes.

In the calibration of the horizontal scale, the tachymeter is placed to the rotary table in such a way that the vertical axis is aligned to the rotational axis of the table (Figure 2). The table is rotated 360° in 30° steps and at each step the reading of the tachymeter that has been targeted to the collimation tube are recorded.

The vertical scale of the tachymeter is calibrated in the same way but now the rotary table is turned to vertical position by using optomechanics that have been designed especially for this purpose.



Figure 2. Calibration of the horizontal plane of a tachymeter in an Eimeldingen rotary table with a collimation tube as a target point.

Contents of tacheometer calibration	Typical measurement uncertainty
Calibration of length scale	
<i>Deviation from reference</i>	
precision target	0.15 mm
spherical target	0.15 mm
reflector tape	0.20 mm
without target	
<i>Calibration of angle scale</i>	
scale error of the vertical circle	2" – 3"
scale error of the horizontal circle	1" – 2"
tilting axis error	1" – 2"
index error of the vertical circle	0.5" – 1.5"
line-of-sight error	0.5" – 1.5"
crosshair alignment and perpendicularity	
influence of focussing	
checking the readings of the environmental sensors	
divergence test of automatic targeting	

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## the obvious